

Non-Perturbative Measurements using Minimum Photon Approaches

■ **Perturbation Limits**

- General physics of x-ray interactions (e.g. cross-sections)
- Perturbation limits of soft and hard matter
- Imaging resolution versus dose

■ **Extracting maximum information from each photon**

- Better algorithms
- Improved optics
- Advanced detectors

■ **Integrated approaches to solving scientific problems**

- X-ray measurements
- Theory and large scale simulation
- Other probes (e.g. TEM, optical spectroscopy)



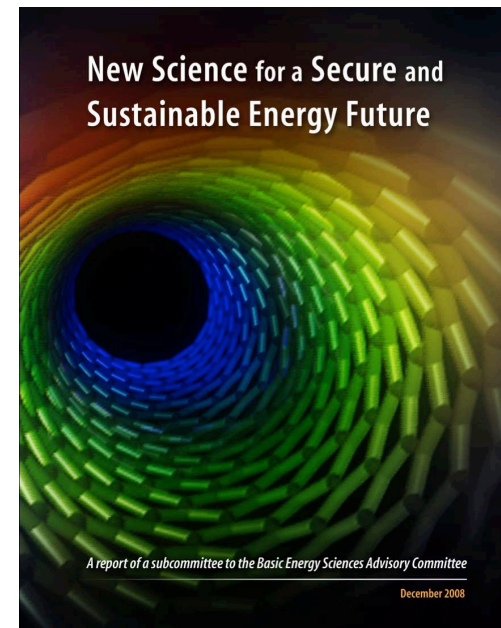
Fundamental Questions in Materials Science

What materials are present?

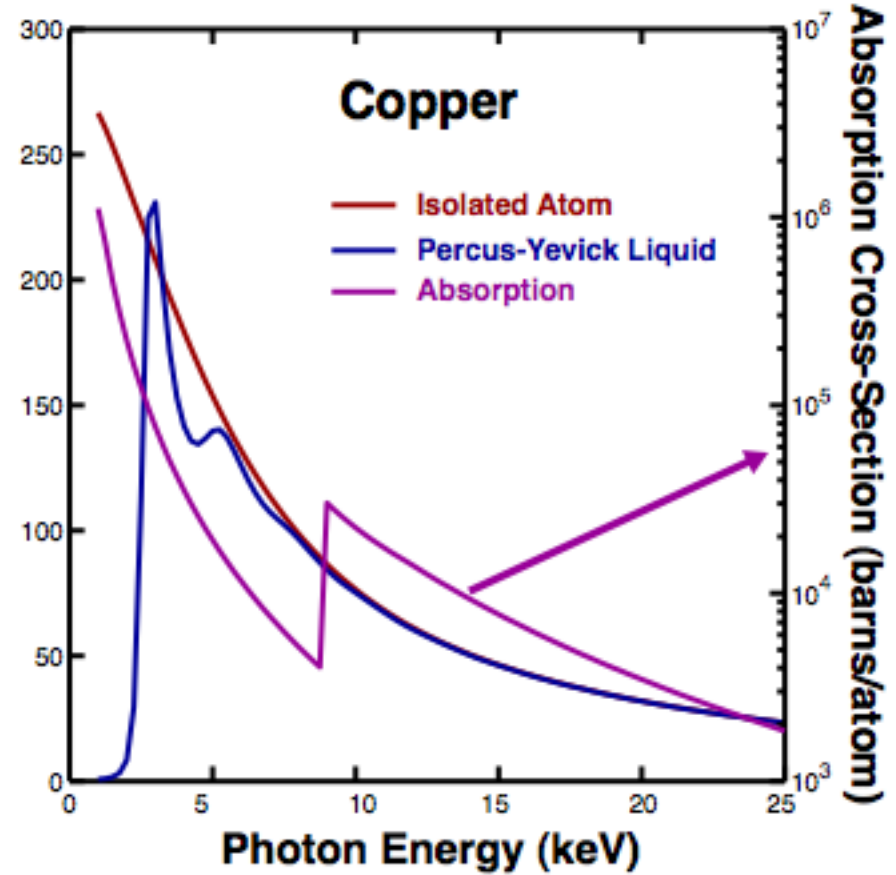
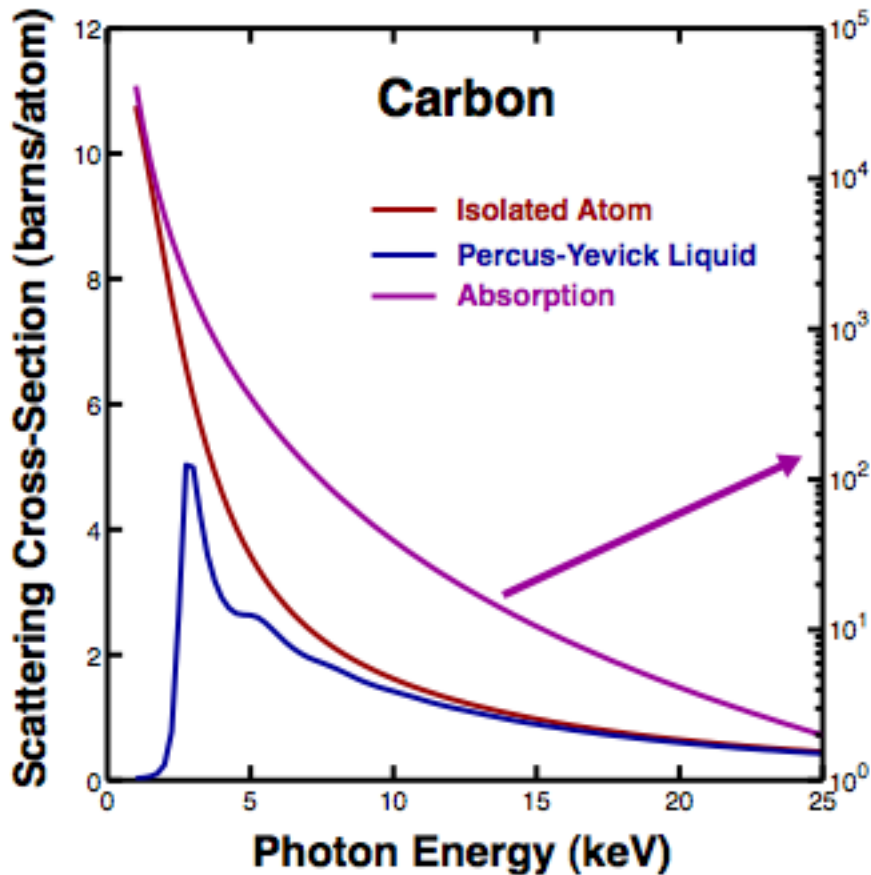
Where are the materials located?

When do crucial transformations and processes occur?

Why does a material have its structure and properties?



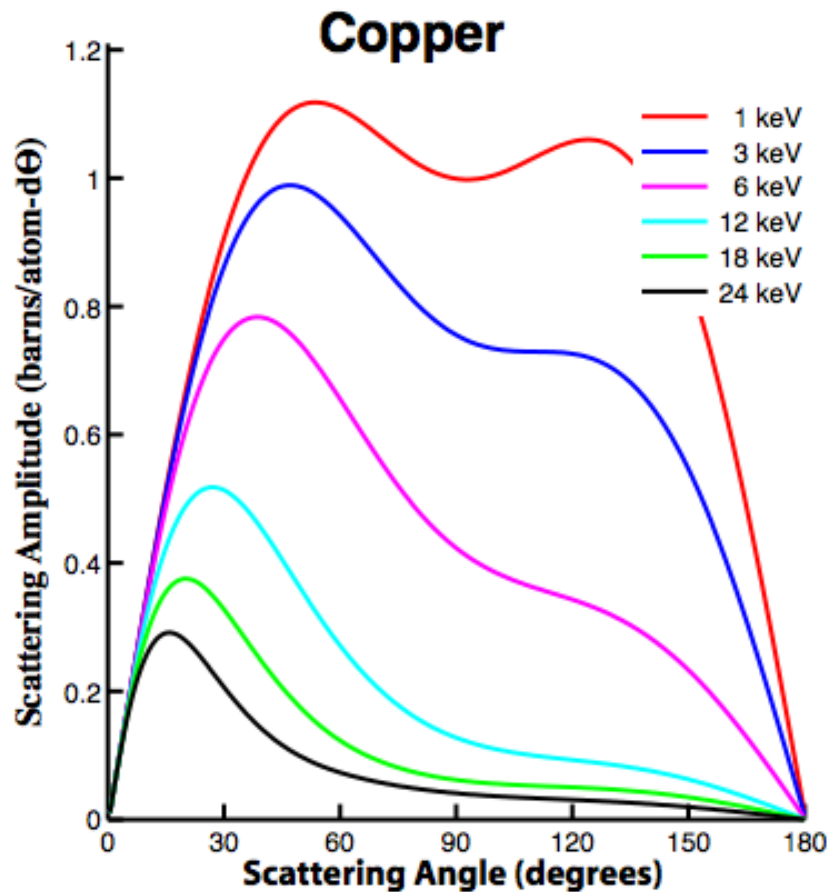
Scattering Calculations: Cross-Sections versus



Note that the absorption cross-section is always much larger than the scattering cross-section



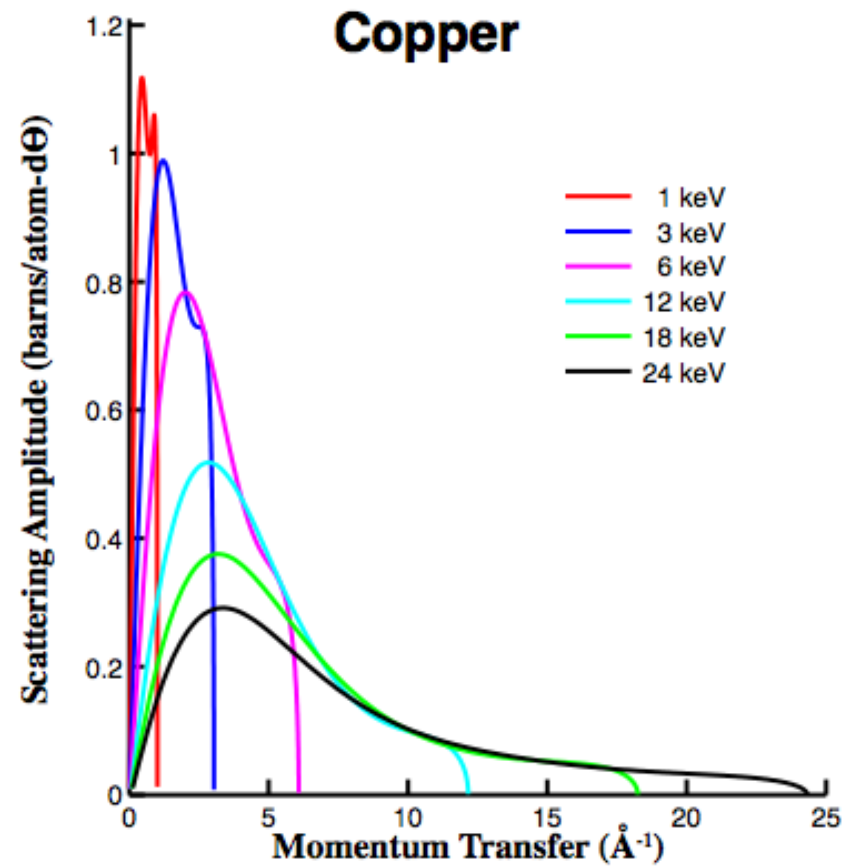
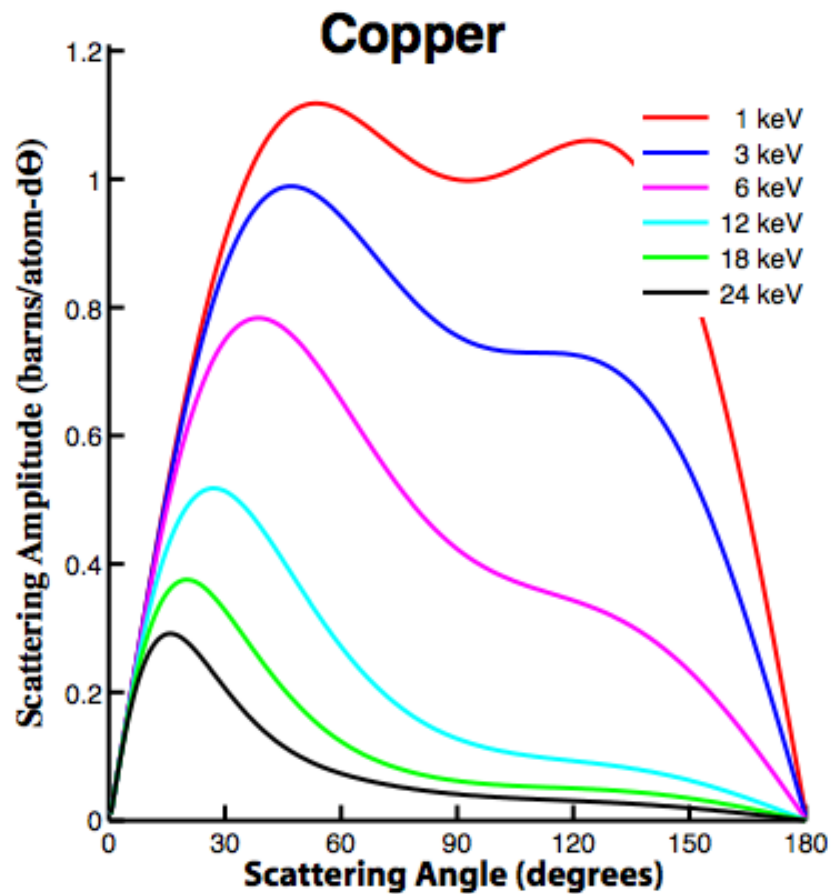
Scattering Cross Section



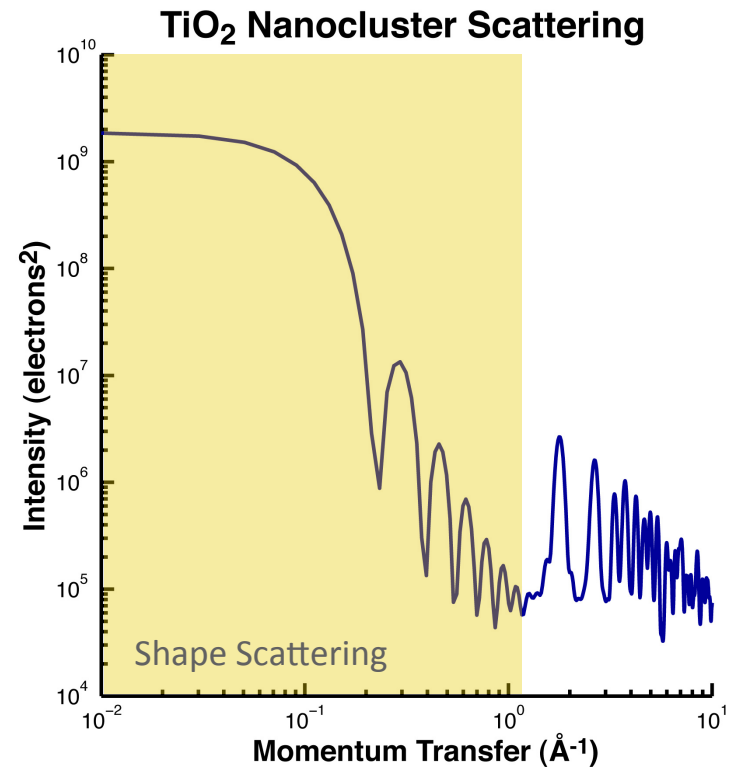
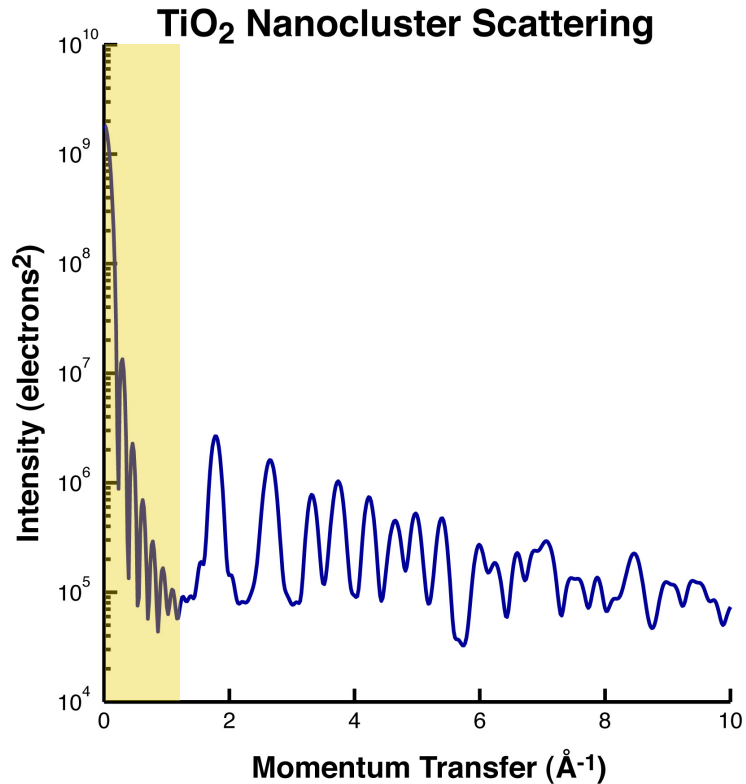
The strong scattering over all of angle space is why crystallographers often prefer to work at lower photon energy (i.e. the scattered intensity is spread out of a large angle space and the integrated intensities are much higher).



Scattering Cross Section

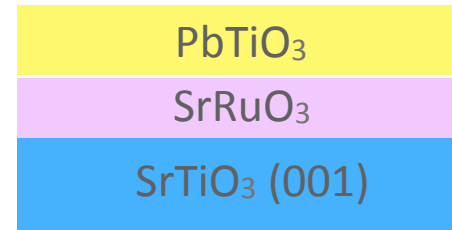
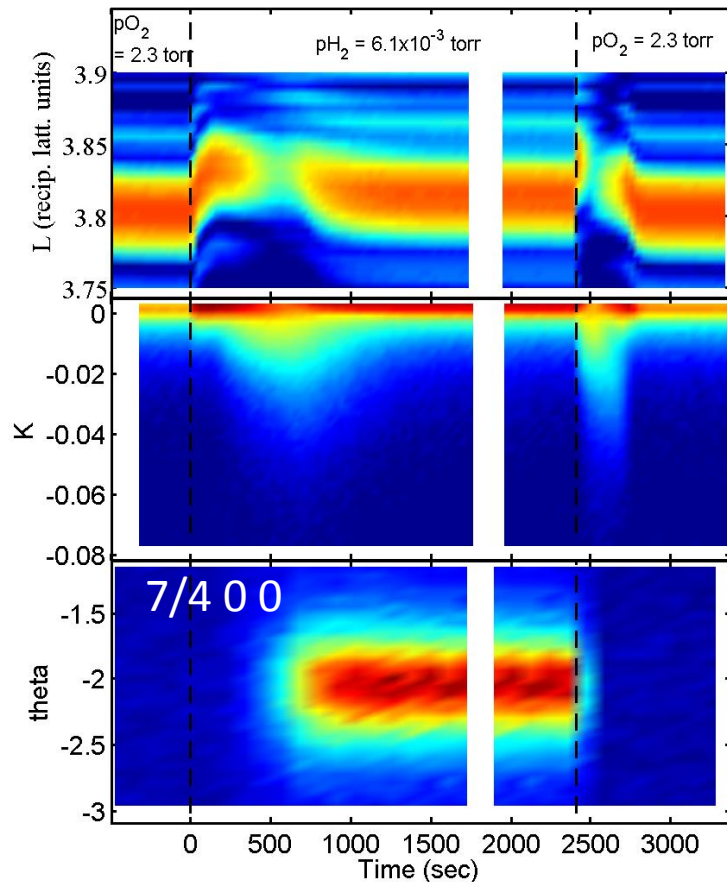


Scattering Calculations: Include Atomic Correlations

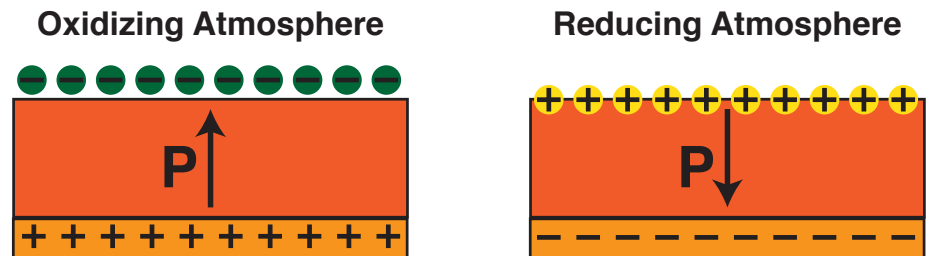


Polarization Switching in Ferroelectric Oxides

The ferroelectric polarity of a thin PbTiO_3 film can be switched by changing the boundary conditions through gas phase chemistry.



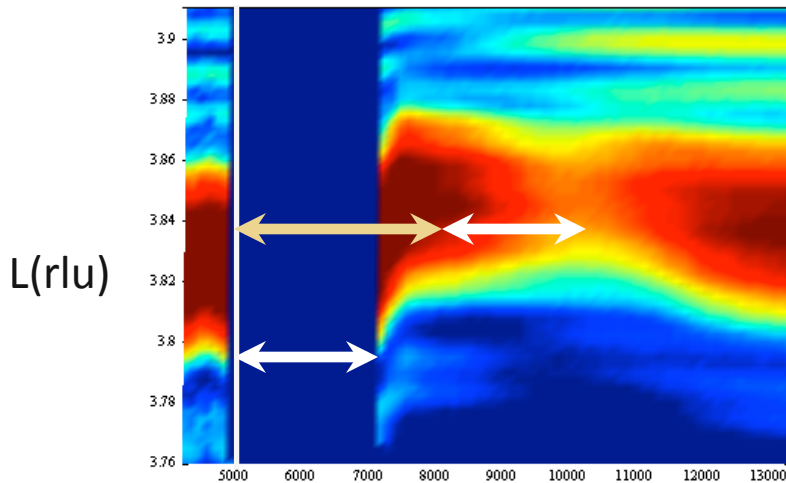
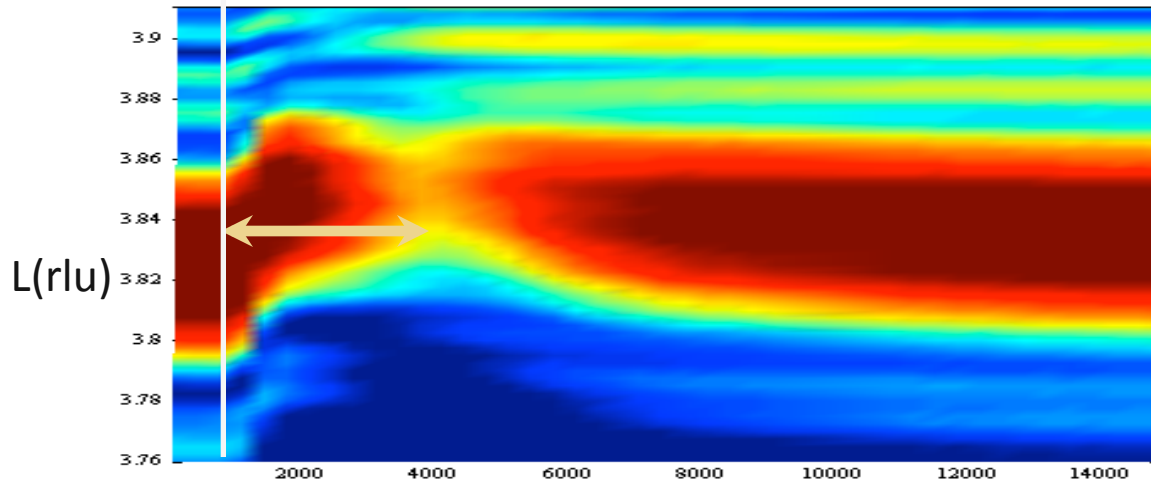
Switching Schematic



X-rays “improve” kinetics of chemical switching

0.23 Torr

2.4×10^{-5} Torr



Elapsed time (sec)

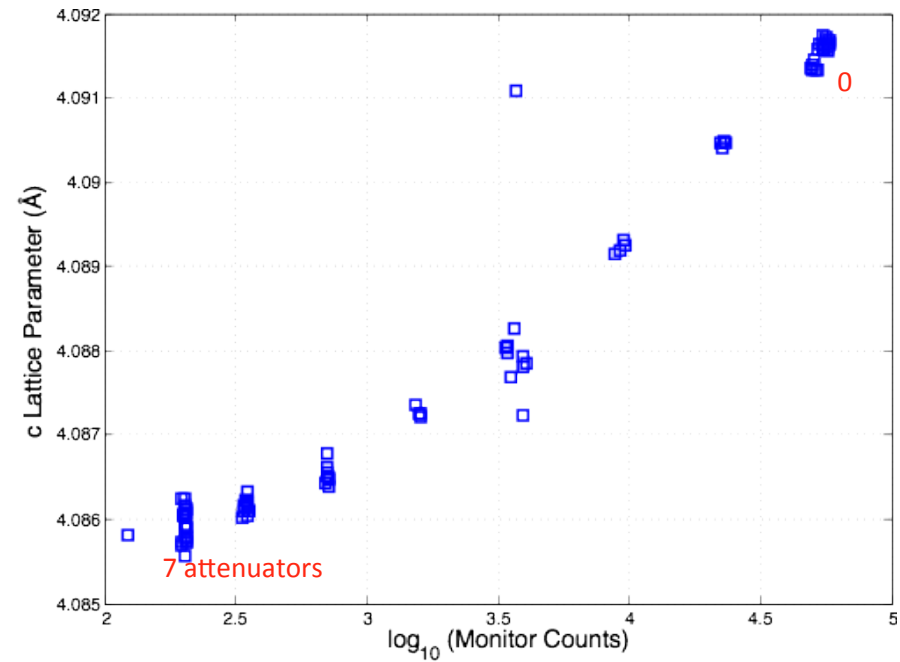
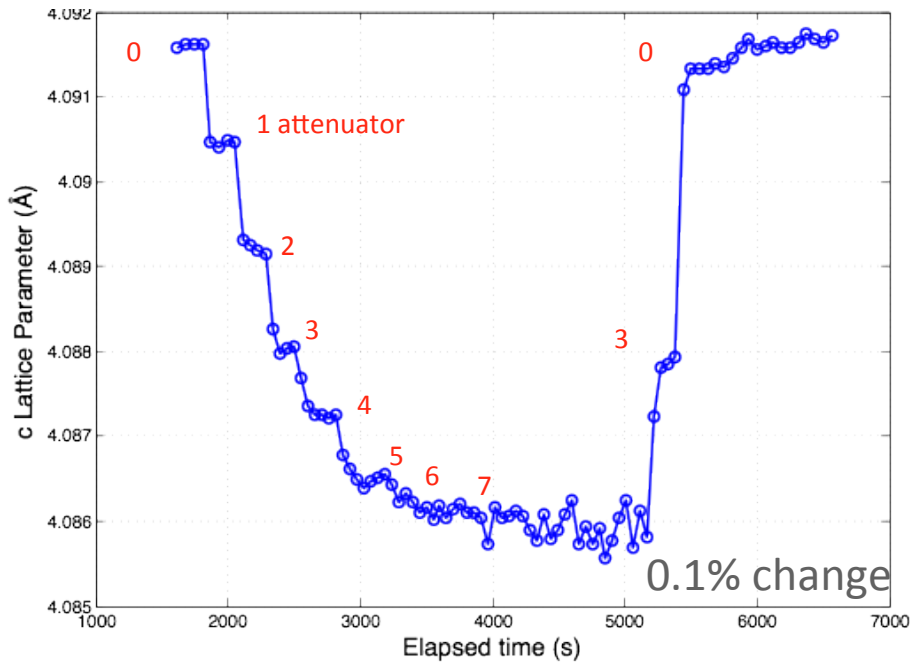
10 nm PTO/SRO/STO at 500C

- up to down switch is the “slow switch” (~ 2800 sec)
→ 0.23 to 2.4×10^{-5} Torr
- time delay in up to down switch \approx time x-rays are off sample



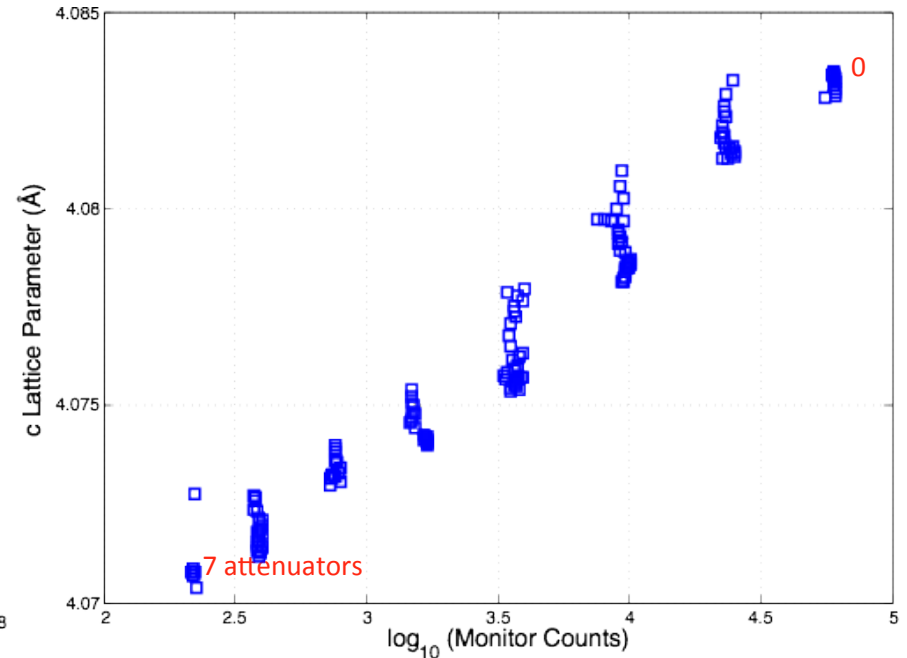
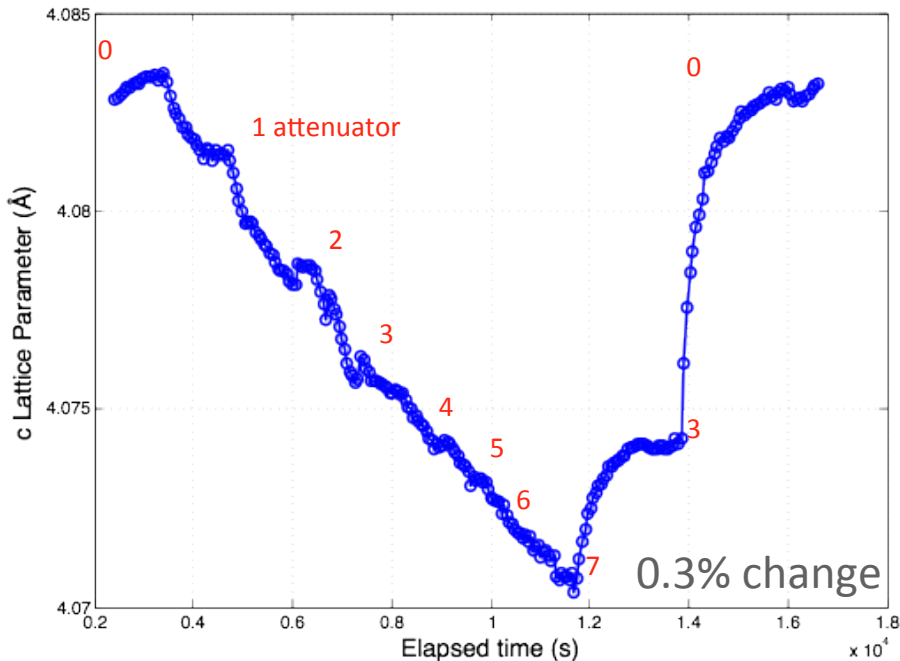
Effect of x-rays on c lattice parameter (monodomain up)

- X-rays help compensate depolarizing field (larger c lattice parameter)
- In the up state (10 nm PTO/SRO/STO at 500C at pO₂=2.3 Torr)
 - fast response to x-rays



Effect of x-rays on c lattice parameter (monodomain down)

- X-rays help compensate depolarizing field (larger c lattice parameter)
- In the down state (10 nm PTO/SRO/STO at 500C at $pO_2=2.4 \times 10^{-5}$ Torr)
 - slower response to x-rays



Damage to Epitaxial PbTiO_3 Film During Ptychography

Main Bragg peak shows partial relaxation out-of-plane lattice parameter.

Also, stripe satellite peaks diminish in intensity and sharpness as PTO stripes become more disordered.

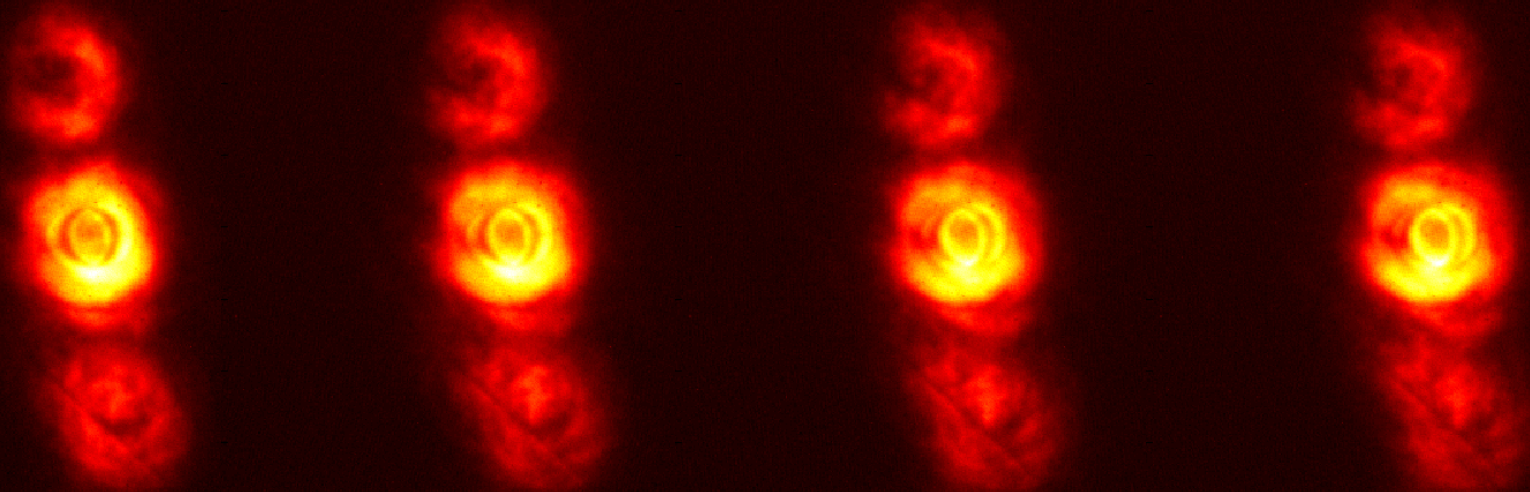
002 PTO peak from a 40-nm diameter spot illuminated repeatedly with 10 second exposures.
After 200 sec of accumulated exposure, changes begin
After 600 sec, we see Bragg peak relaxation and stripe disorder.

1st point

20th point

40th point

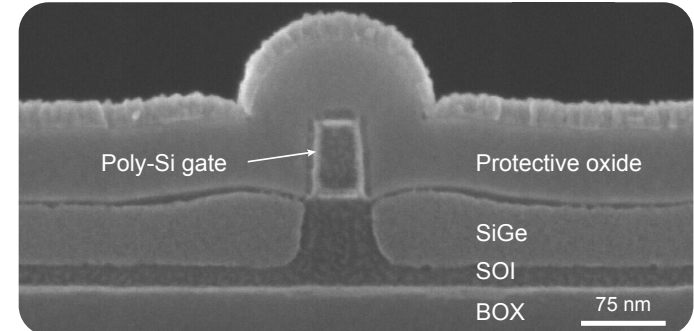
60th point



Stress and Strain are Key to Mesoscopic Behavior

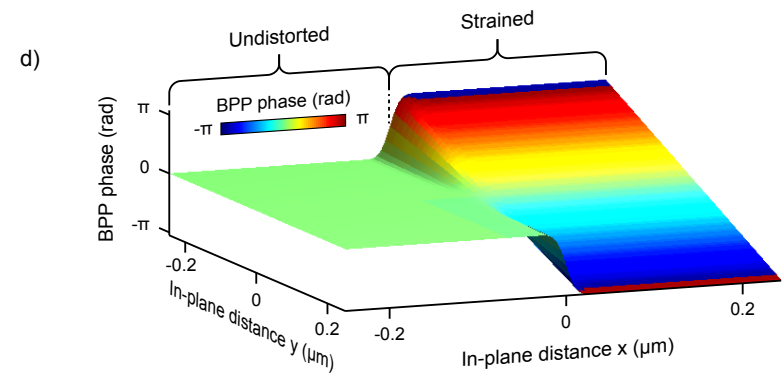
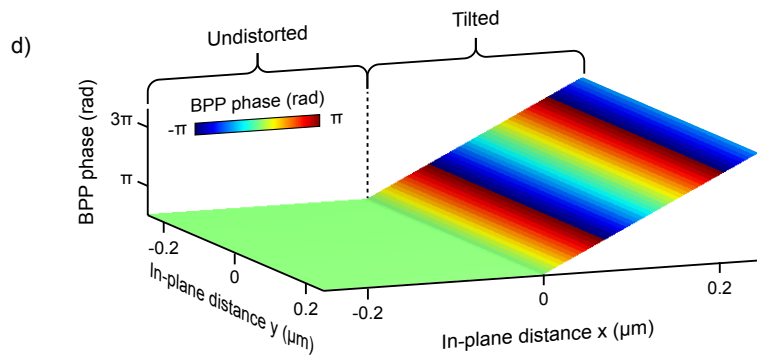
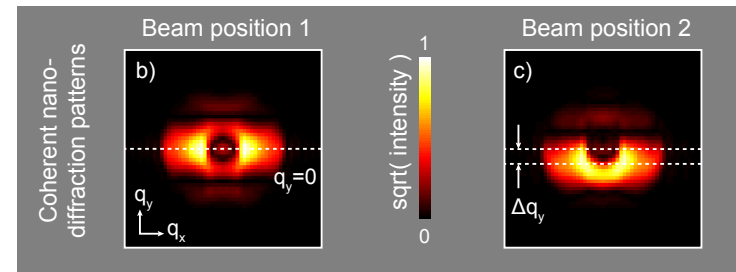
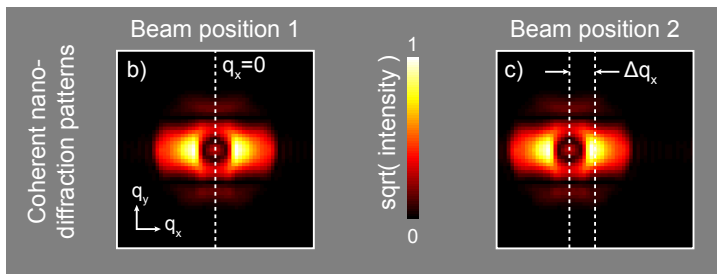
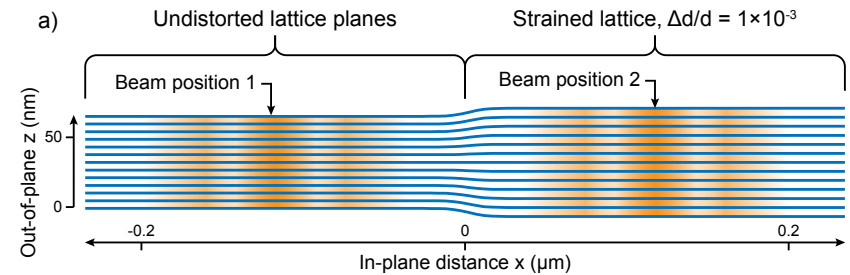
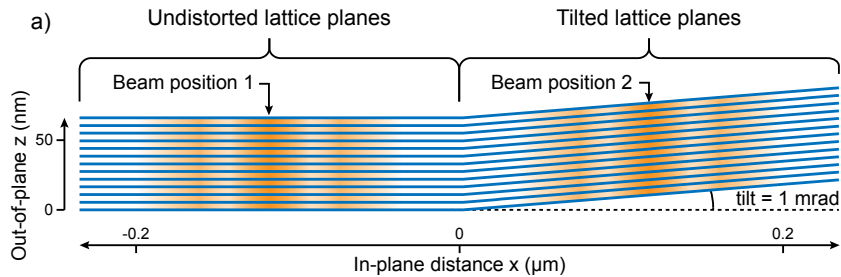
- Stress and strain are important materials parameters available to manipulate properties and performance.
- Control and prediction of lattice responses is challenging since they depend on the complete environment and processing history.
- Measurement and visualization of lattice distortions is necessary to understand the structure and performance in mesoscale systems.
- Studies must be done *in operando* to avoid changing the device boundary conditions.

Example: SiGe stressor layers are used to locally modify band structure and improve silicon device performance.

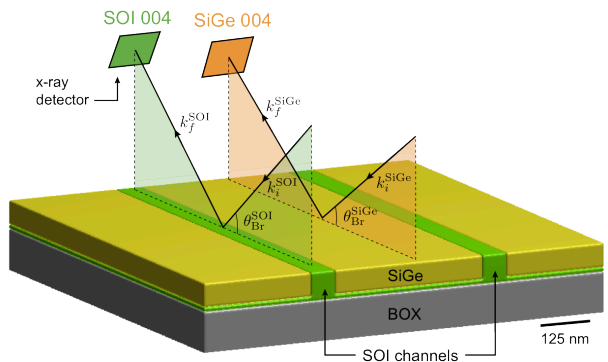


3D Bragg ptychography has great potential for *in operando* studies

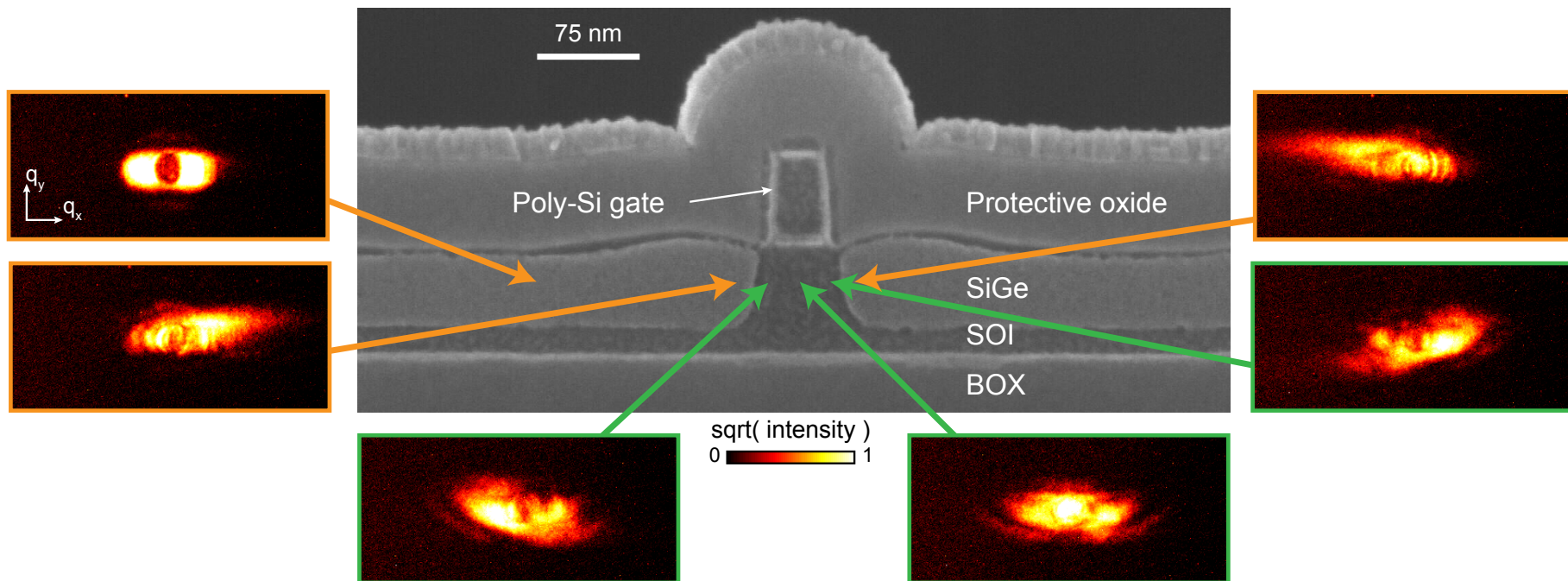
Difference between Tilt and Strain



Nanodiffraction from SiGe Device



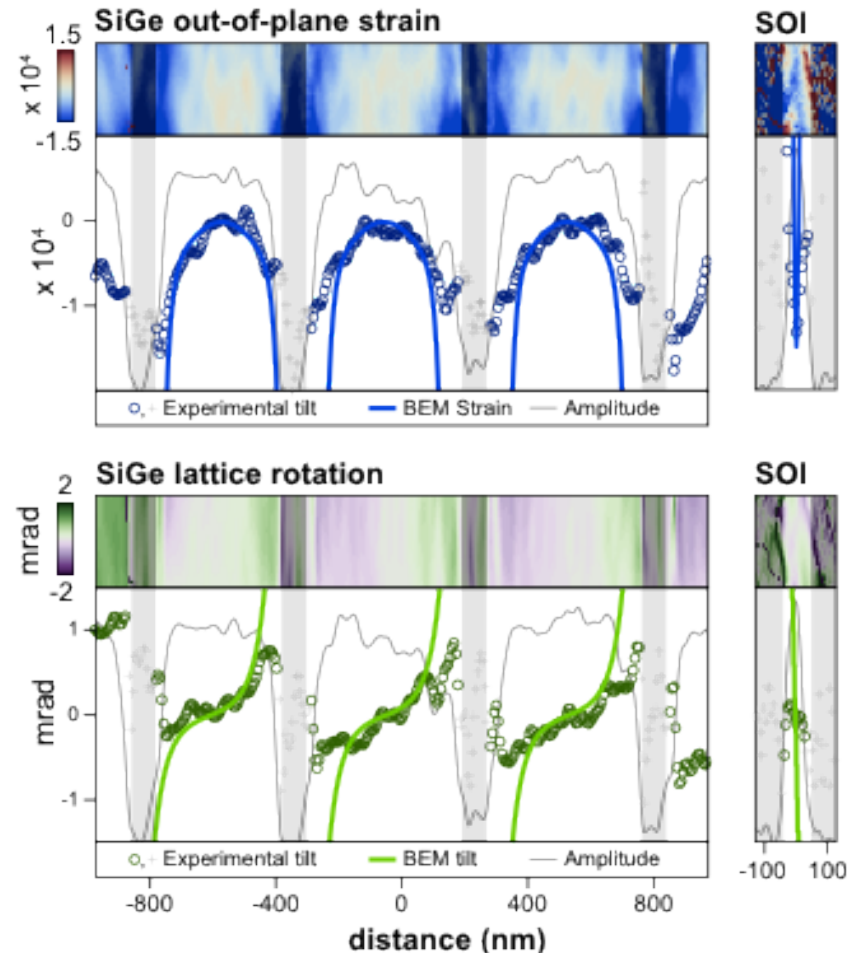
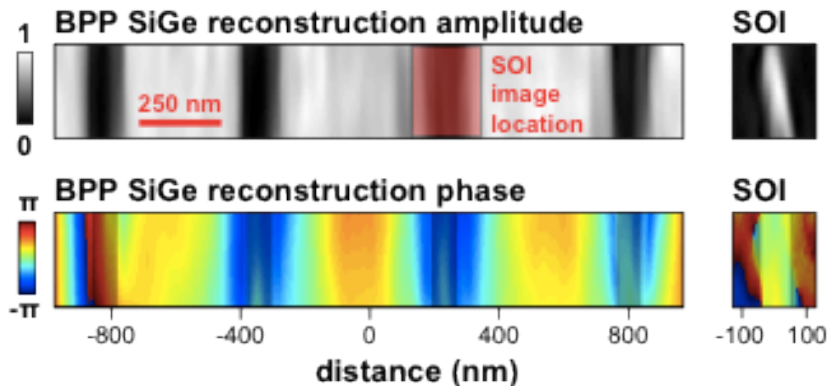
Work by Martin Holt, Stephan Hruszkewycz, Conal Murray, Judson Holt, Debbie Paskiewicz and PHF



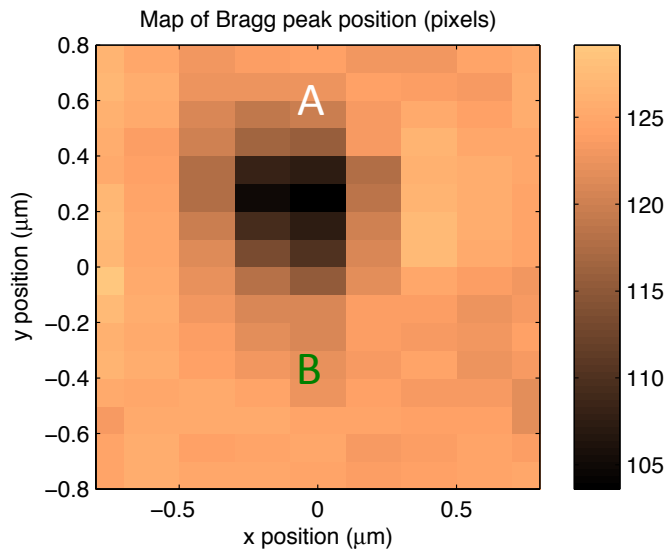
SiGe Device Strain and Deformation

Modeling almost exactly reproduces our BPP reconstruction.

Boundary element method (BEM) calculation shows that there should be both tilts and strain near the active channel.



Damage to Epitaxial SiGe on SOI

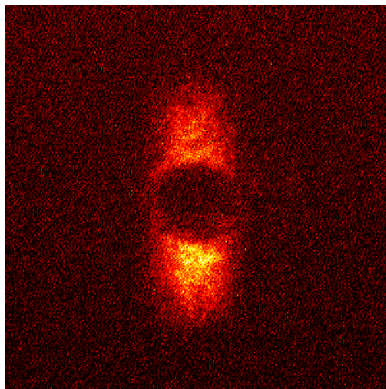


Black region is location of a ptychography spiral scan: 1000 pts, $\sim 600\text{nm}$ diameter, 10 sec exposures, 40nm focused beam diameter, 13nm step size, 65% overlap.

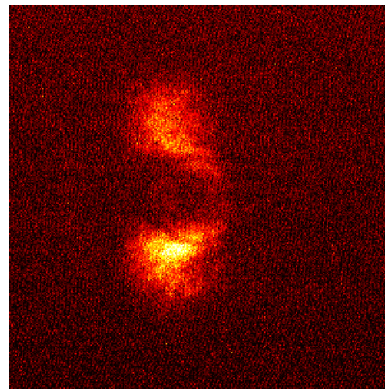
Estimate of flux, 9×10^8 in the focused spot

Scan shown taken with < 1 sec exposures to assess damage, plotted as Bragg peak centroid along the 2θ direction

Position B, undisturbed



Position A, modified

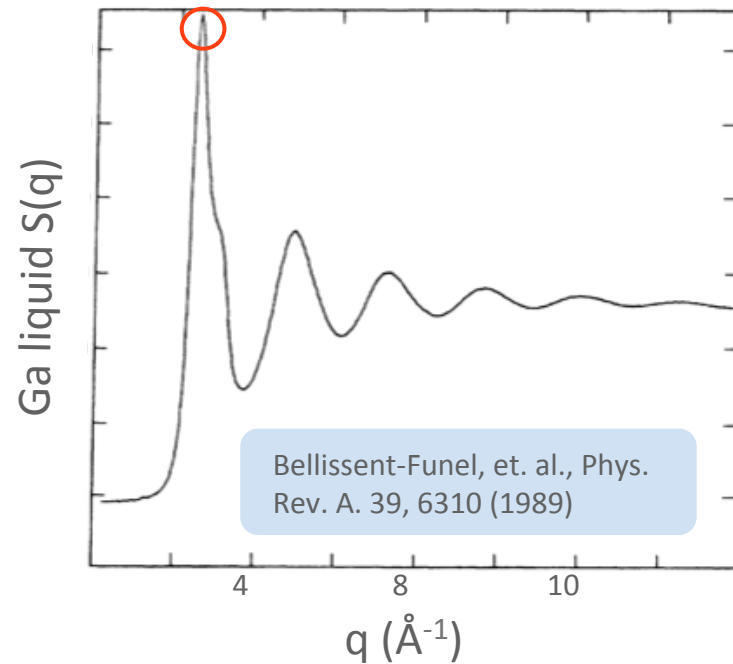
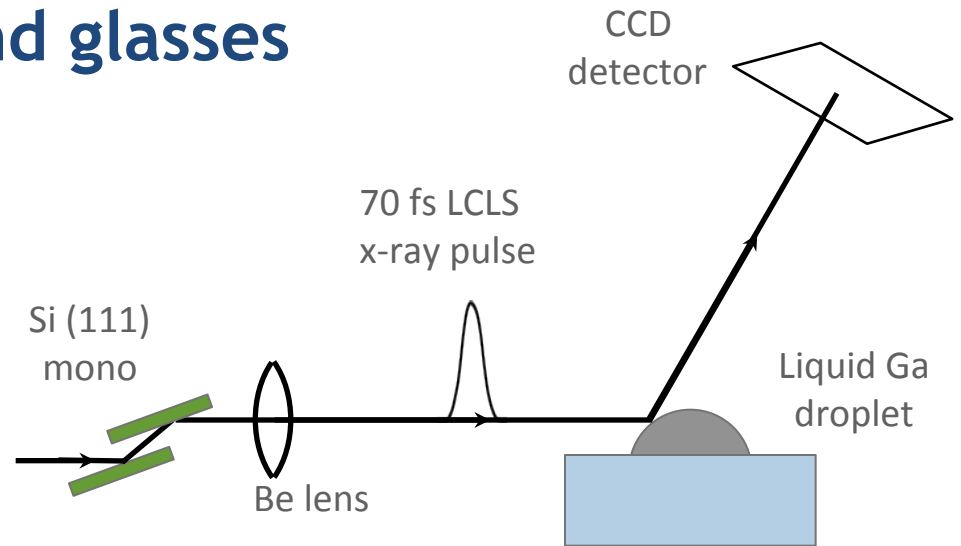


**Relaxed film peak
Shifted to high- 2θ**

Scattering from liquids and glasses

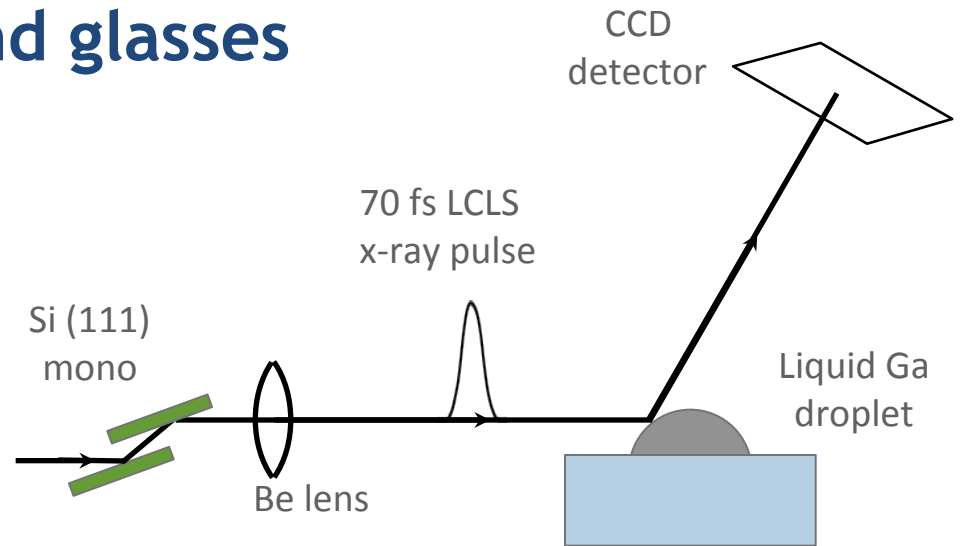
Scattering from atomic liquids and glasses was collected at the LCLS with single and multi-pulse exposure at atomic resolution ($q \approx 3 \text{ \AA}^{-1}$)

- XPP hutch at LCLS
- High angle diffracted speckle recorded by CCD
- Samples:
 - $\text{Pd}_{40}\text{Ni}_{40}\text{P}_{20}$ -> heavy glass
 - B_2O_3 -> light glass
 - Ga -> atomic liquid
- Si (111) monochromator
- Be lenses focus to 1.7 microns

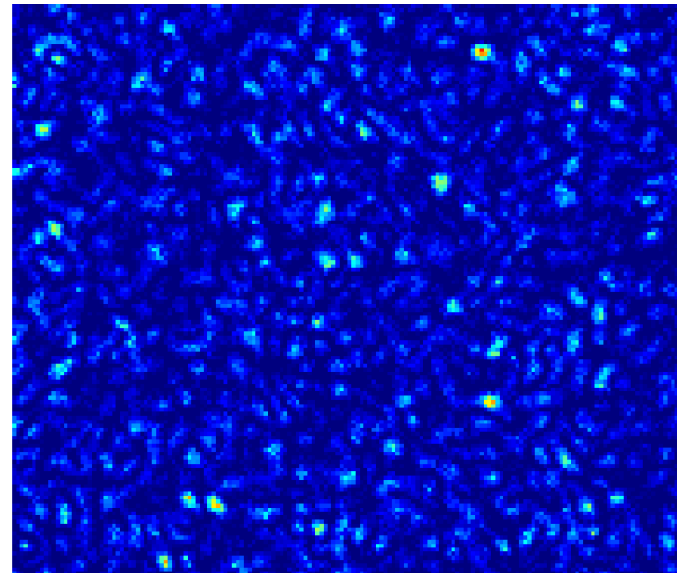


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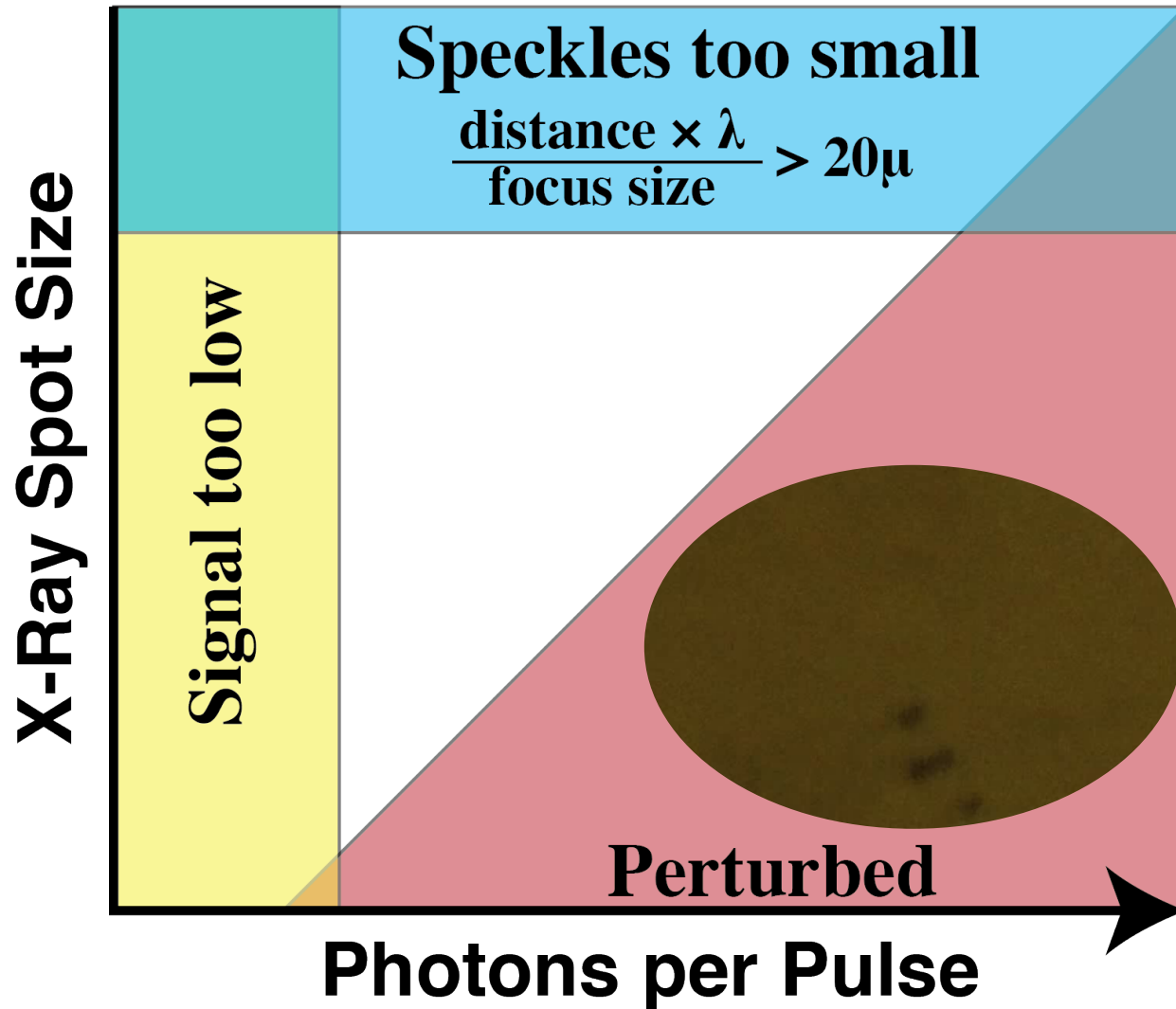
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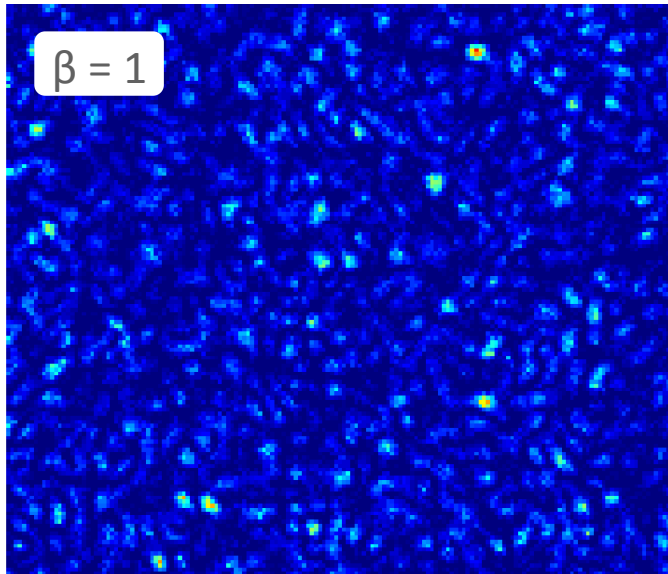


Is There a Useful Non-Perturbative Window?

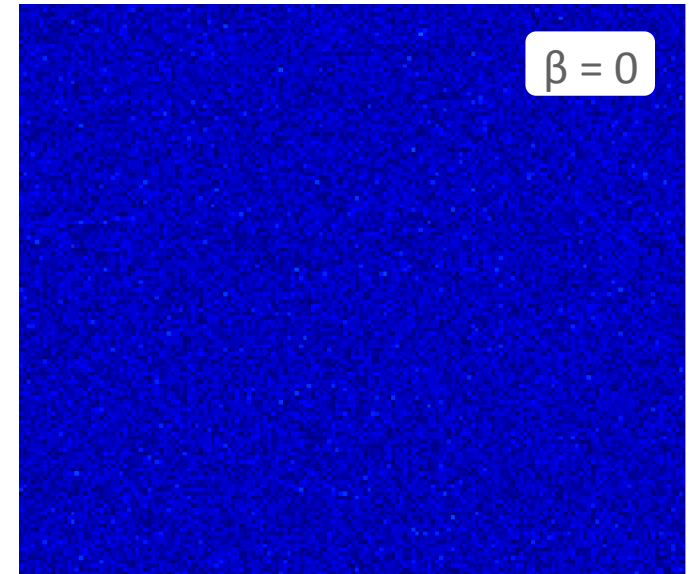


Noise and Speckle

Coherent Speckle



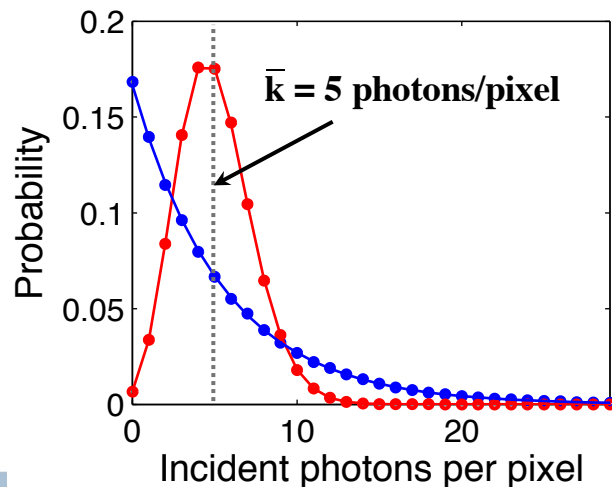
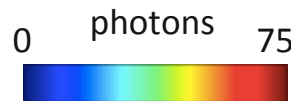
Poisson "Shot Noise"



Contrast

$$\beta \equiv \frac{1}{M}$$

Mean count rate:
5 photons / pixel



Observed probabilities

- Poisson image
- Coherent speckle image

Probability distribution functions

— Poisson: $P_{pois}(k, \bar{k}) = \bar{k}^k e^{-\bar{k}} / k!$

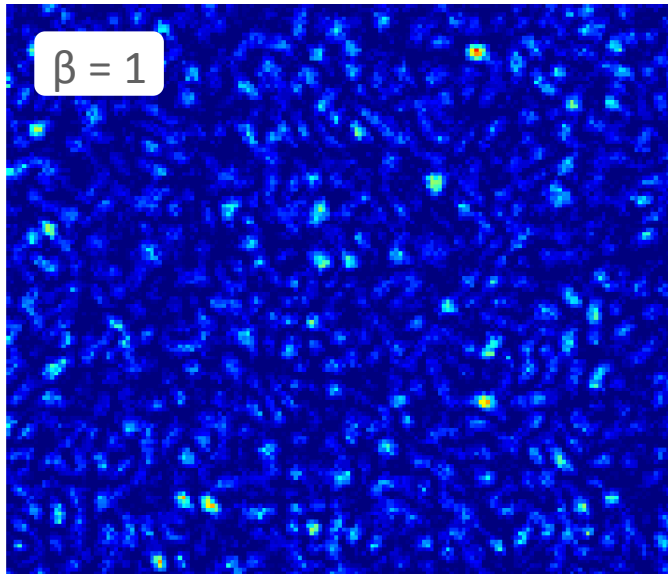
— Negative Binomial (M=1):

$$P_{NB}(k, \bar{k}, M) = \frac{\Gamma(k+M)}{\Gamma(M)\Gamma(k+1)} \left(1 + \frac{M}{k}\right)^{-k} \left(1 + \frac{\bar{k}}{M}\right)^{-M}$$

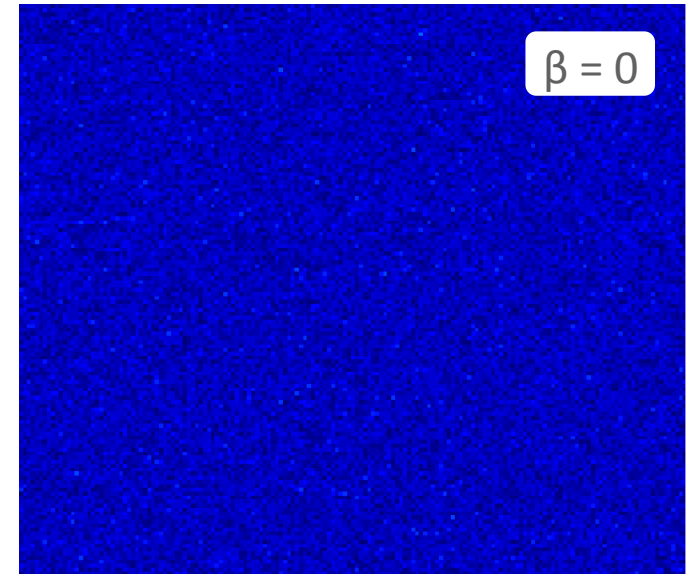


Noise and Speckle

Coherent Speckle



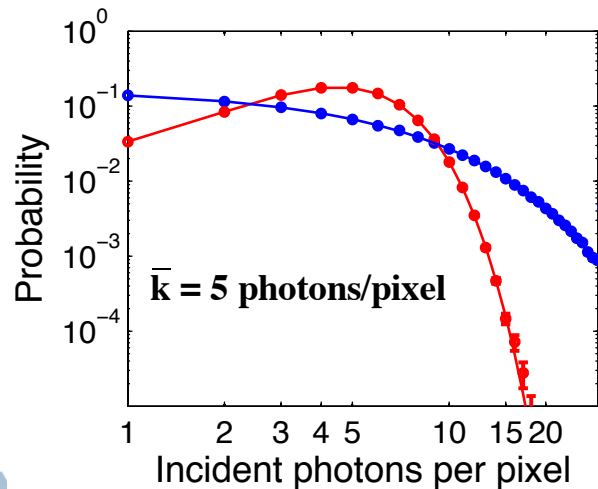
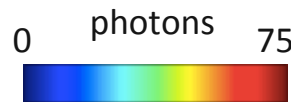
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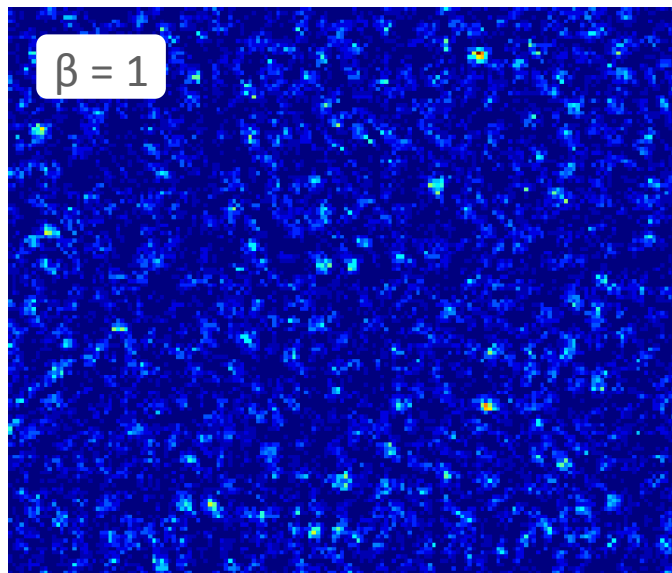
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Noise and Speckle

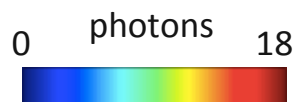
Coherent Speckle



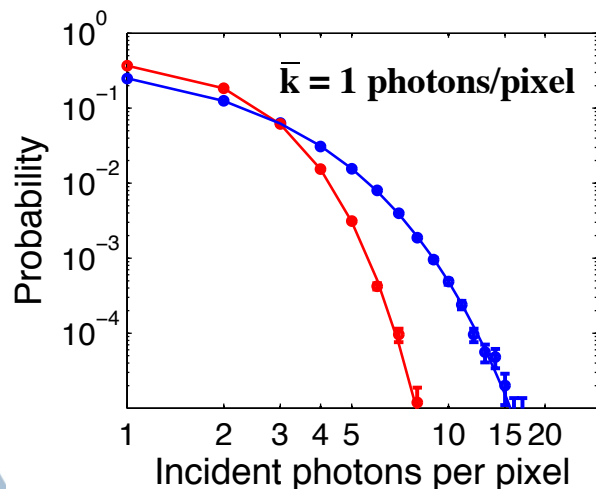
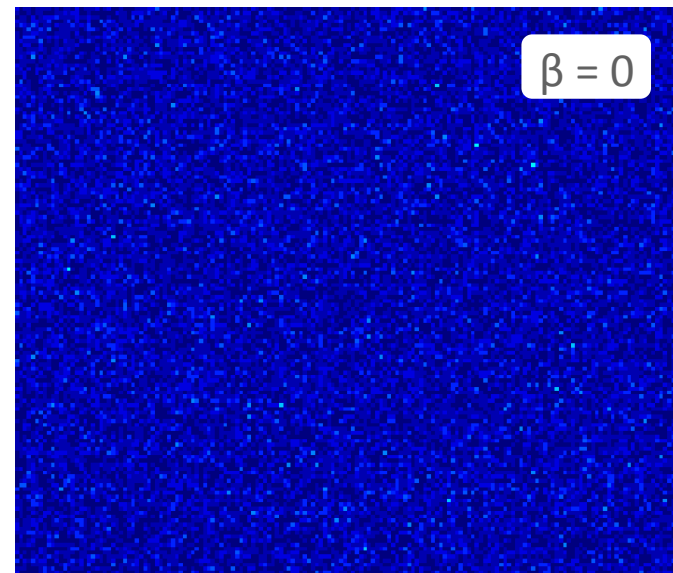
Contrast

$$\beta \equiv \frac{1}{M}$$

Mean count rate:
1 photons / pixel



Poisson "Shot Noise"



Observed probabilities

- Poisson image
- Coherent speckle image

Probability distribution functions

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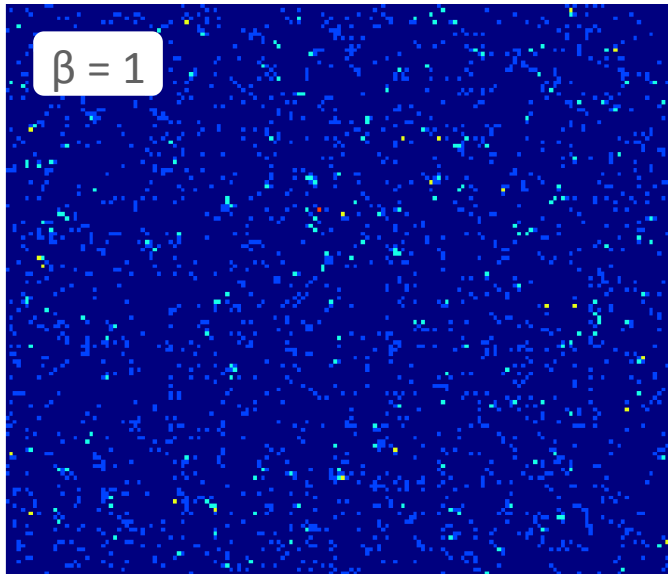
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Noise and Speckle

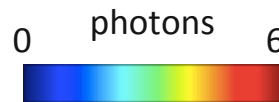
Coherent Speckle



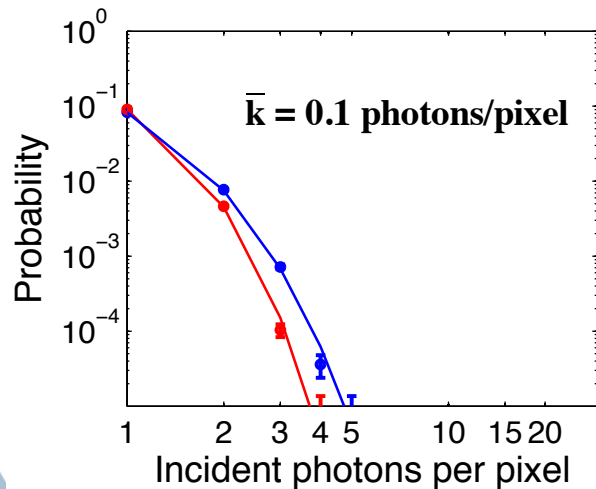
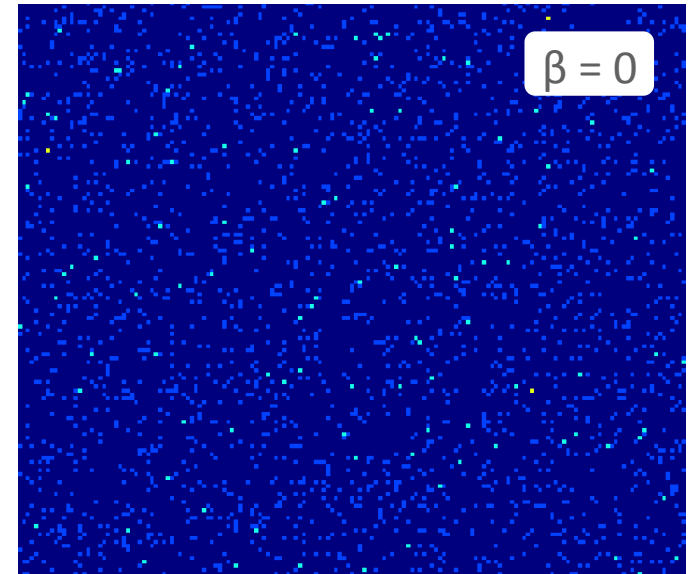
Contrast

$$\beta \equiv \frac{1}{M}$$

Mean count rate:
0.1 photons / pixel



Poisson “Shot Noise”



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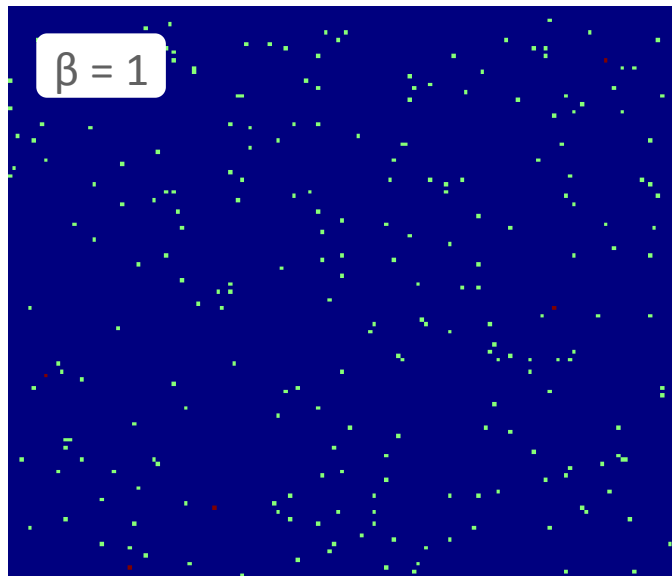
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Noise and Speckle

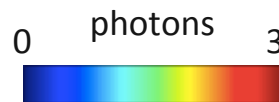
Coherent Speckle



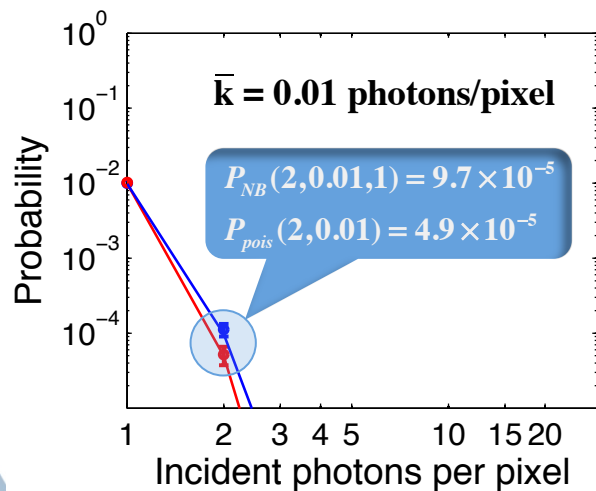
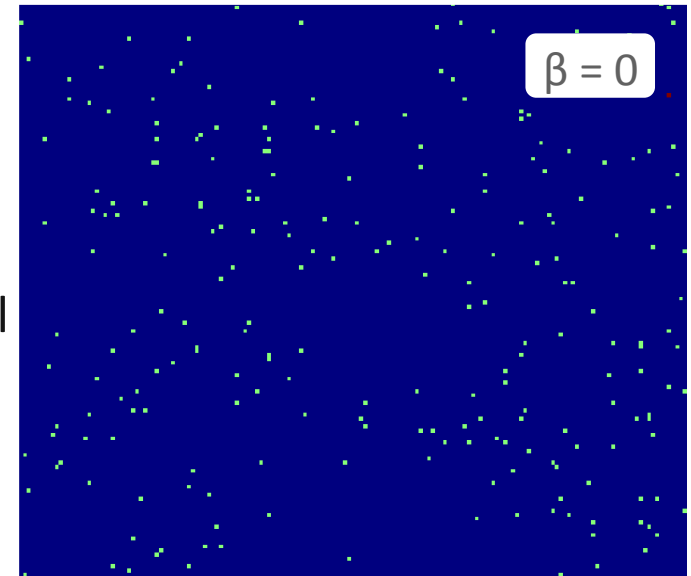
Contrast

$$\beta \equiv \frac{1}{M}$$

Mean count rate:
0.01 photons / pixel



Poisson "Shot Noise"



Observed probabilities

- Poisson image
- Coherent speckle image

Probability distribution functions

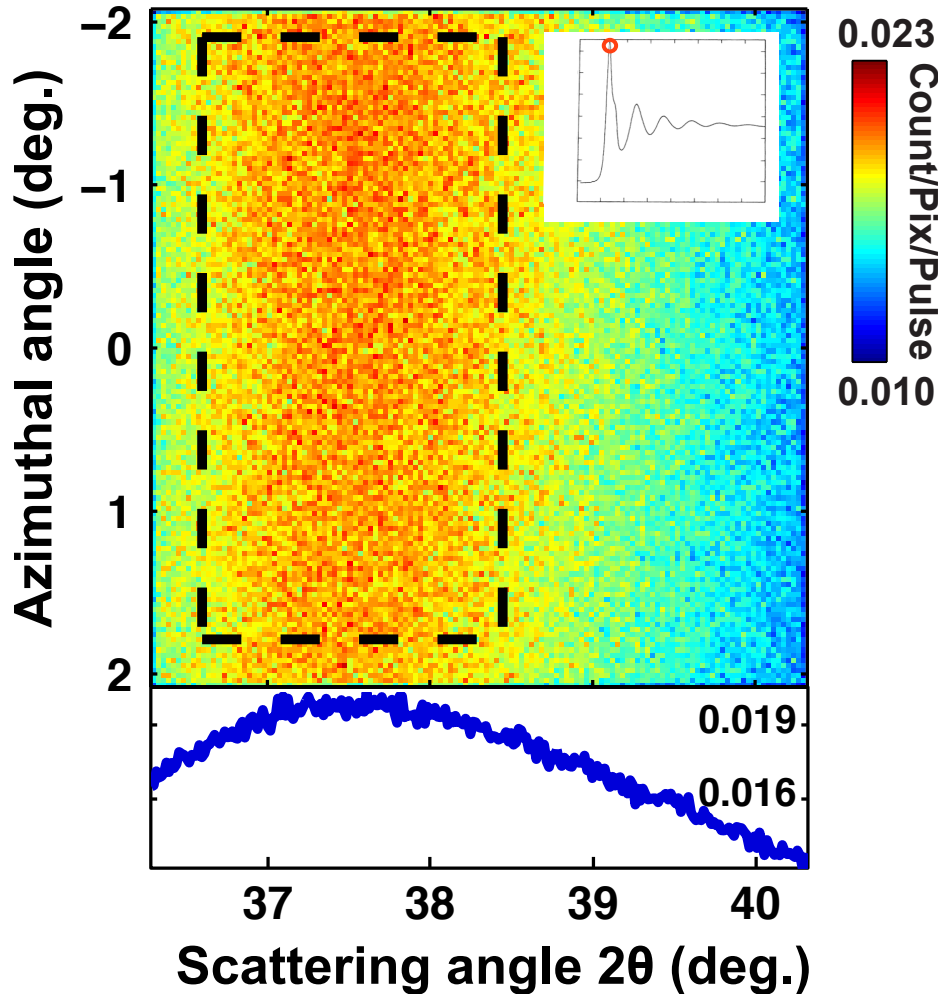
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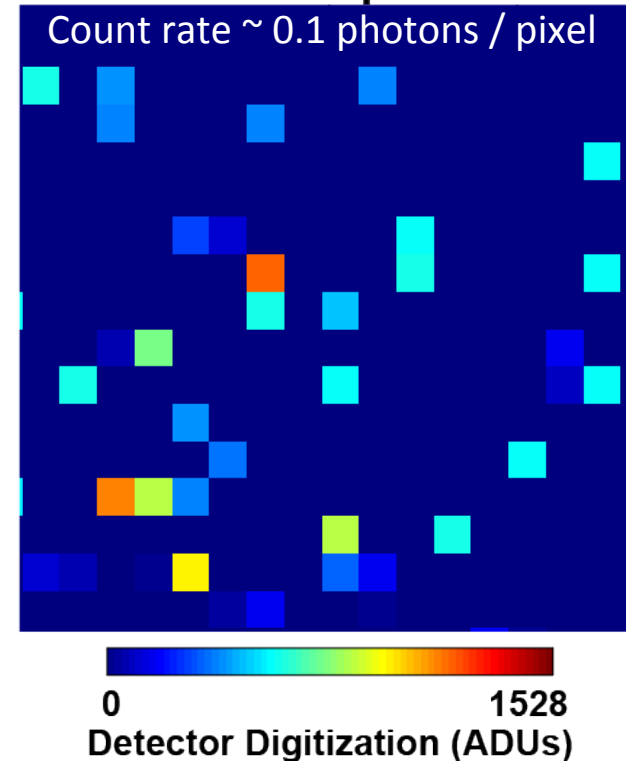
High angle liquid scattering

Single pulse scattering patterns are very weak and need to be carefully analyzed in order to determine contrast.

Summation of 500 shots



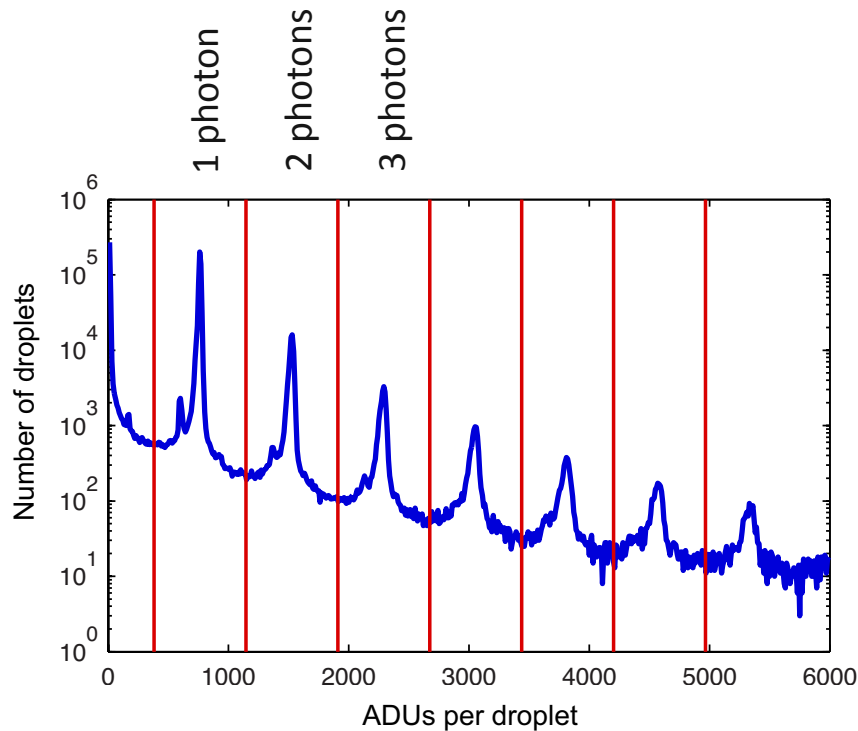
Detector pixels



The droplet algorithm

Step 1: Identify regions of connectivity, i.e. droplets

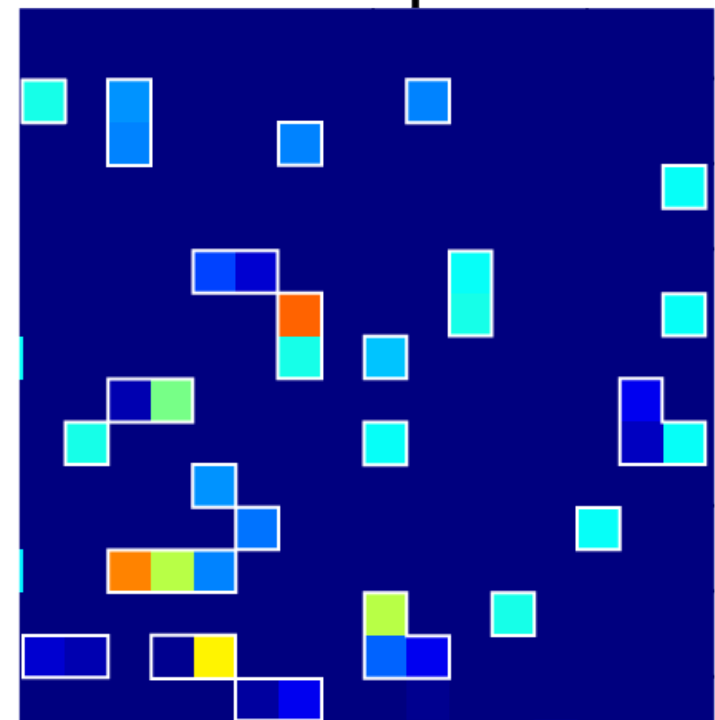
- **Histogram of droplets by their total counts clearly separates photon events**



F. Livet et al., Nucl. Instrum. Meth. A 451, 596 (2000).

Droplets accurately identify regions of correlated intensity.

Detector pixels



0 1528
Detector Digitization (ADUs)



The droplet algorithm

Step 1: Identify regions of connectivity, i.e. droplets

- Histogram of droplets by their total counts clearly separates photon events

Step 2: Fit each droplet by least squares to identify positions of photons

Step 3: After photons were extracted, they were re-gridded onto the detector pixels.

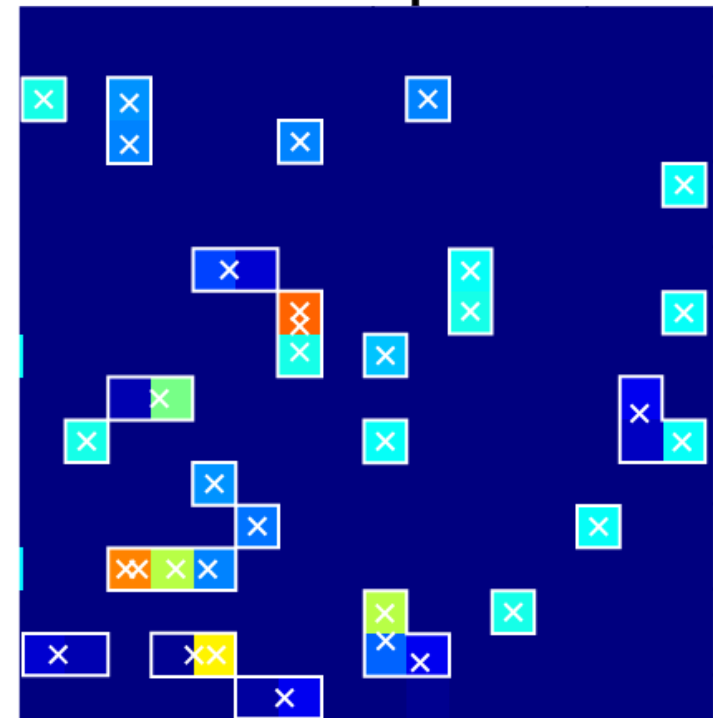
- **Accurate determination of P(1) and P(2)**

$$P(1) \approx \bar{k} - (1 + \beta)\bar{k}^2$$

$$P(2) \approx \frac{(1 + \beta)\bar{k}^2}{2} - \frac{(1 + \beta)(1 + 2\beta)\bar{k}^3}{2}$$

Technique identifies the x,y coordinate of every photon.

Detector pixels



0 1528
Detector Digitization (ADUs)



Measuring contrast from liquid Ga

Experimental considerations define maximum attainable contrast:

$$\beta_{calc}(p, L, Q, t, \theta, \Delta E / E, s_x, s_y)$$

The experimental value

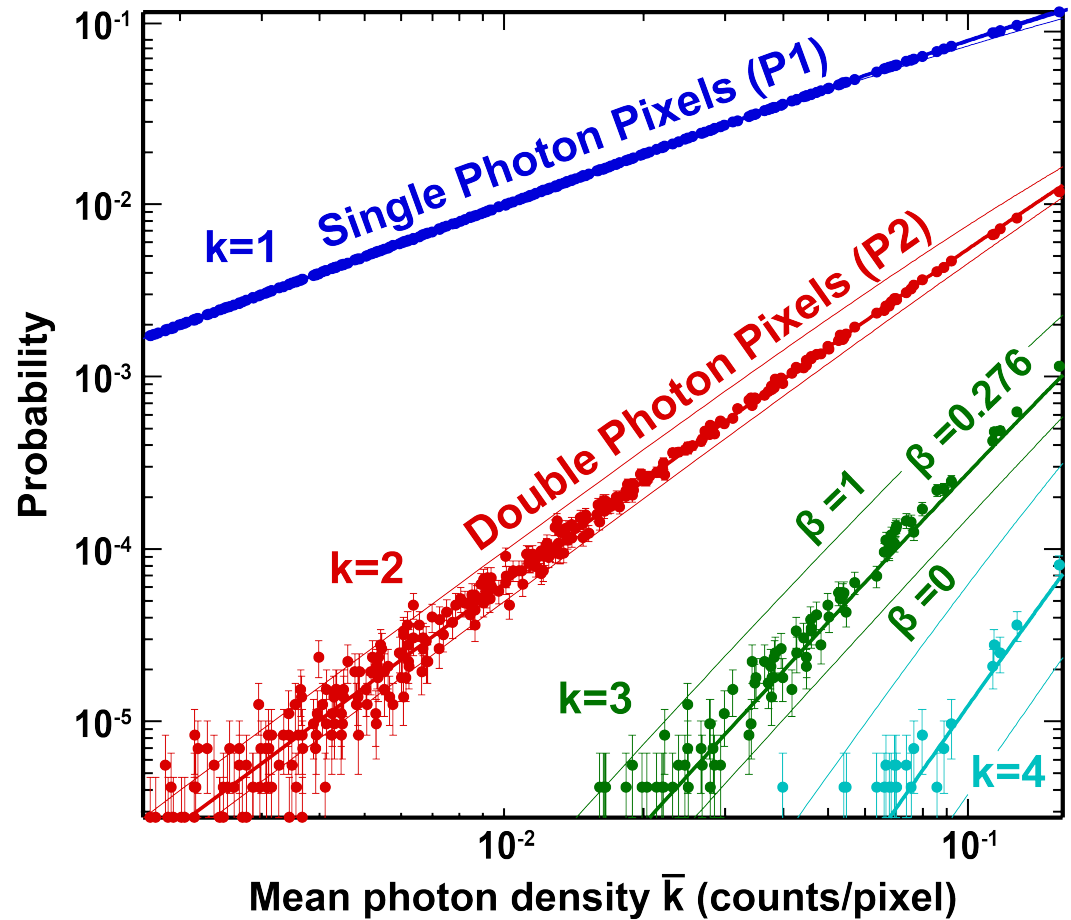
$$\beta_{Ga} = 0.276 \pm 0.004$$

was determined from droplet fitting analysis, and matches the maximum attainable

$$\beta_{calc} = 0.307$$

for this geometry

$$P_{NB}(k, \bar{k}, M) = \frac{\Gamma(k+M)}{\Gamma(M)\Gamma(k+1)} \left(1 + \frac{M}{k}\right)^{-k} \left(1 + \frac{\bar{k}}{M}\right)^{-M}$$

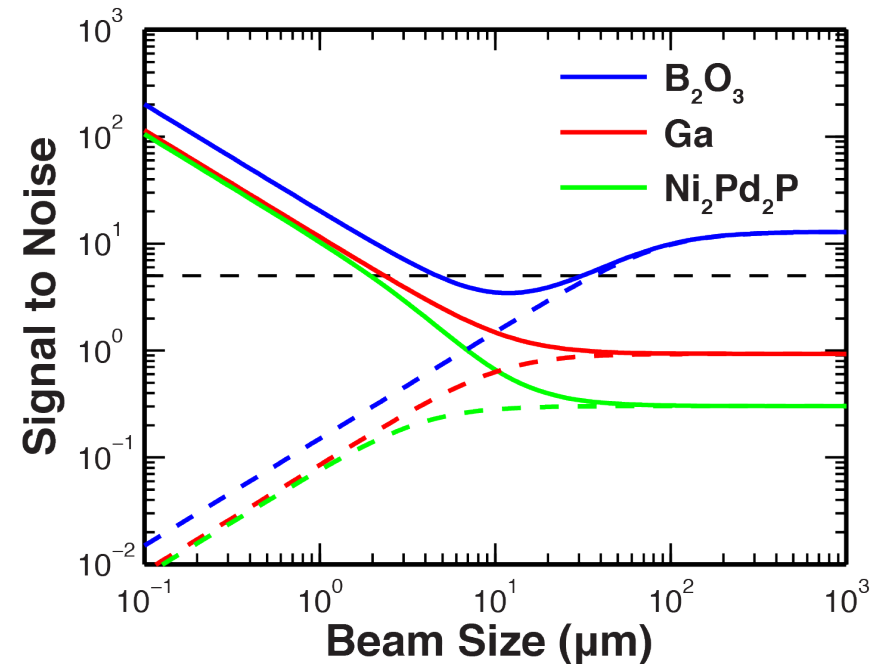
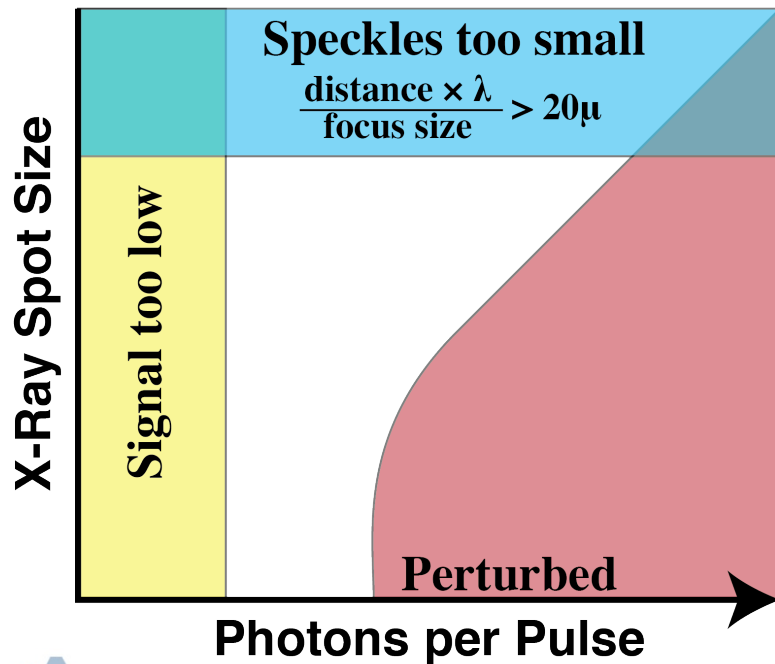
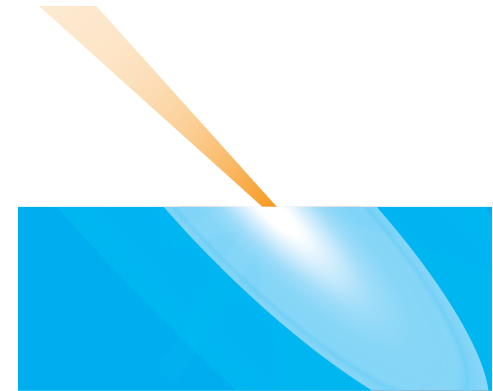


(Note the large range of incident pulse energies)



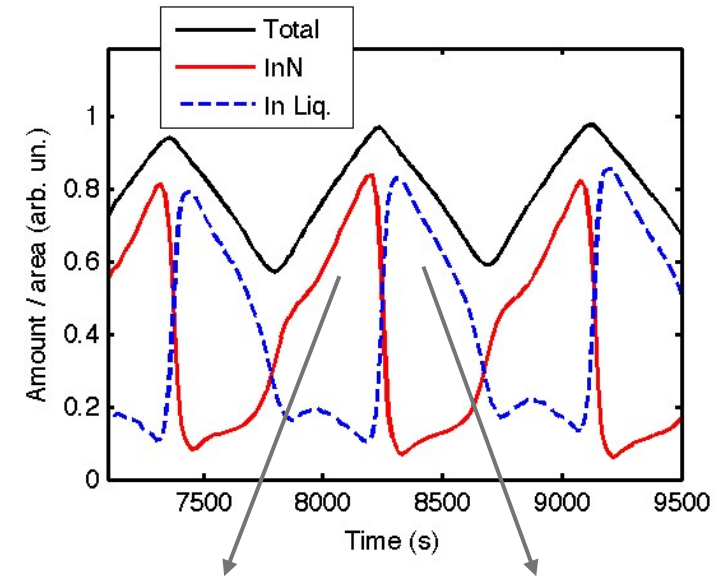
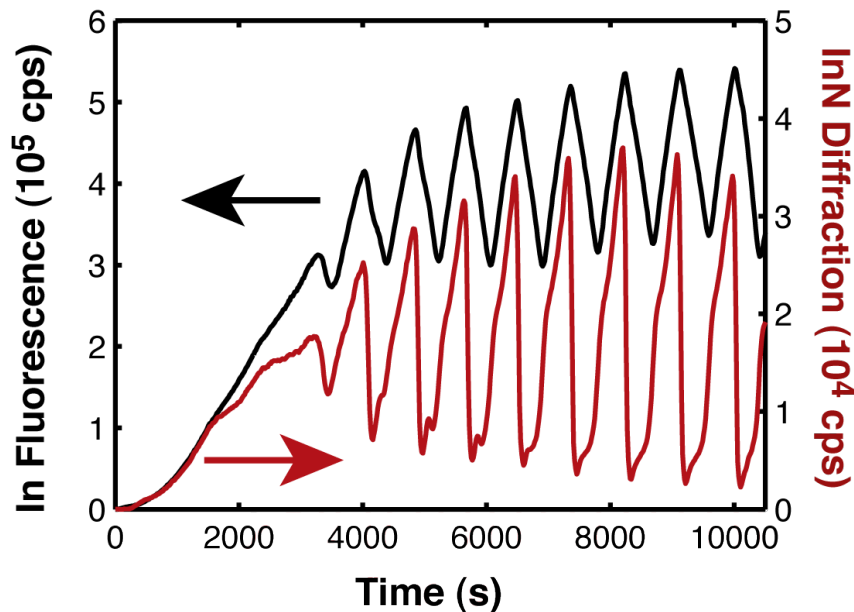
X-Ray Energy Deposition is Larger Than Focus

- Most of the x-ray energy is carried away by high energy electrons and fluorescent photons that have a range of many microns.
- Energy is deposited well outside a sub-micron focus.
- **Sample perturbation doesn't scale like the inverse of the focal spot size.**



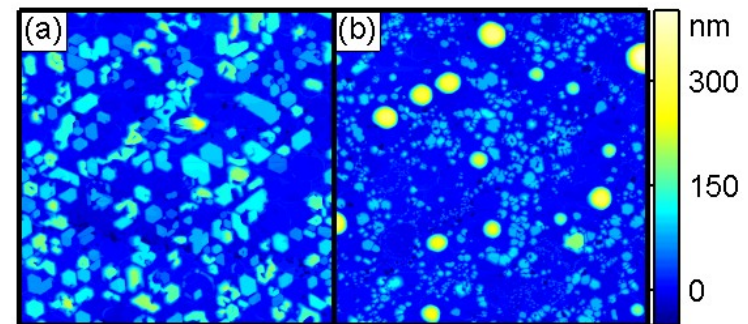
Oscillatory Growth and Decomposition

- Near phase boundaries system can spontaneously oscillate
 - Inter-conversion between InN and liquid In
- AFM of quenched samples shows microstructure of distinct surface species



Epitaxial InN islands

Elemental In droplets



F. Jiang, et al. PRL 101, 086102 (2008)

Real-time Observations of Chemical Waves during Oscillatory Growth and Decomposition of InN

Oscillatory Pattern Formation during MOCVD of InN on GaN

1. Expanding circular pattern

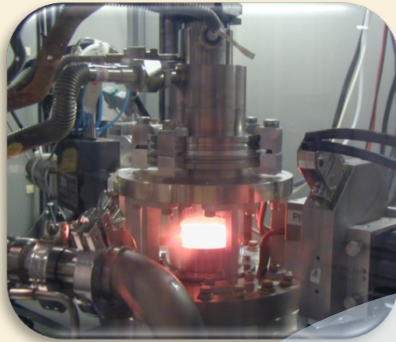
Actual elapsed time:	1 hour 25 min
Temperature:	664°C
TMI flow rate:	0.145 $\mu\text{mol}/\text{min}$
NH ₃ partial pressure:	27 Torr
Total pressure:	200 Torr
Sample size:	15x15 mm ²



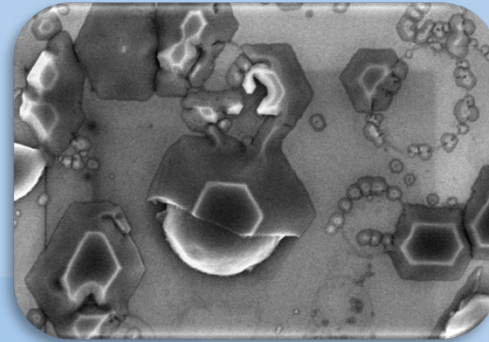
Attacking the Problem on Multiple Fronts

Understanding complicated problems such as WBG synthesis and fabrication requires a variety of *in-situ* probes and computational techniques

In-situ X-ray Analysis



X-Ray Imaging of Defects



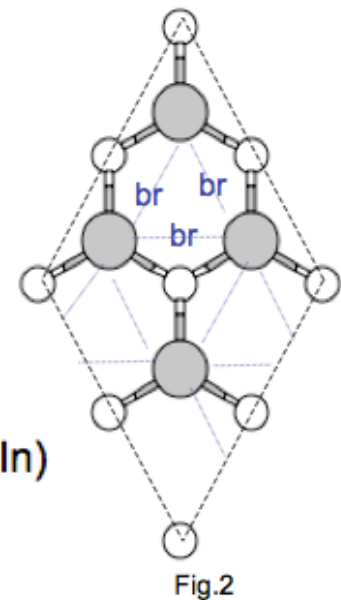
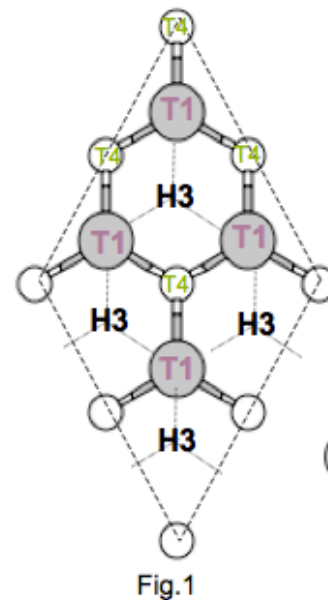
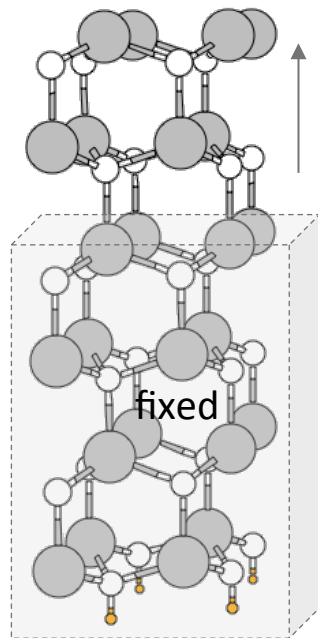
Theory & Modeling

First-principles Calculations

- Calculate the lowest energy configurations of NH_3 , NH_2 , NH , N , and H on a GaN and InN surface
- Create a phase diagram predicting the equilibrium coverage species for given conditions

- (2x2) surface unit cell
- 4 H3 “hollow” sites
 - 4 T1 “on top” Ga sites
 - 4 T4 “on top” N sites
 - 12 br “bridge” site

~ 10^3 structures possible



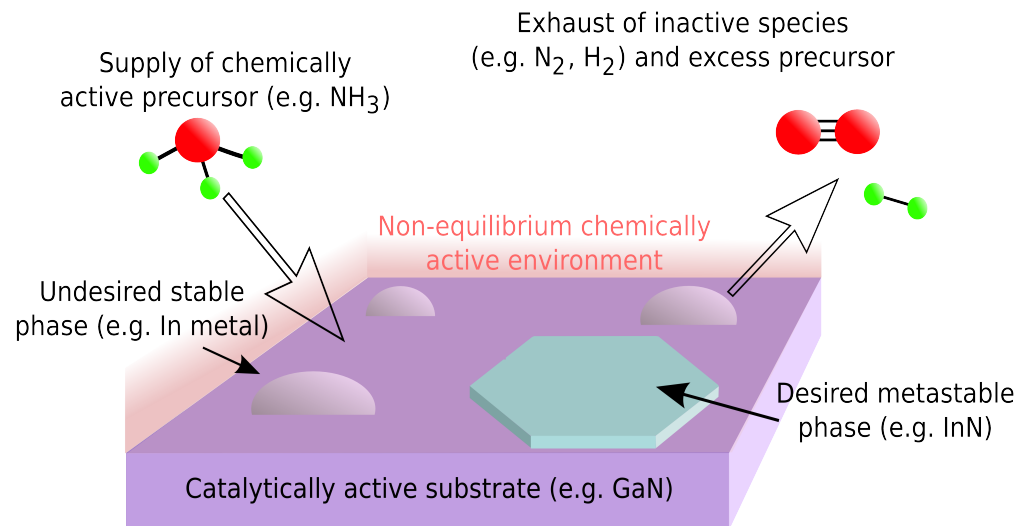
“We” = Peter Zapol, Weronika Walkosz, and Xin Tan

Intermediate Chemical Species

- The local intermediate chemical species dictate growth behavior
- Different surfaces catalytically crack NH_3 differently and possibly change residence time of intermediate species
- If we can understand which intermediate species enable InN growth, then we can better stabilize and encourage its formation

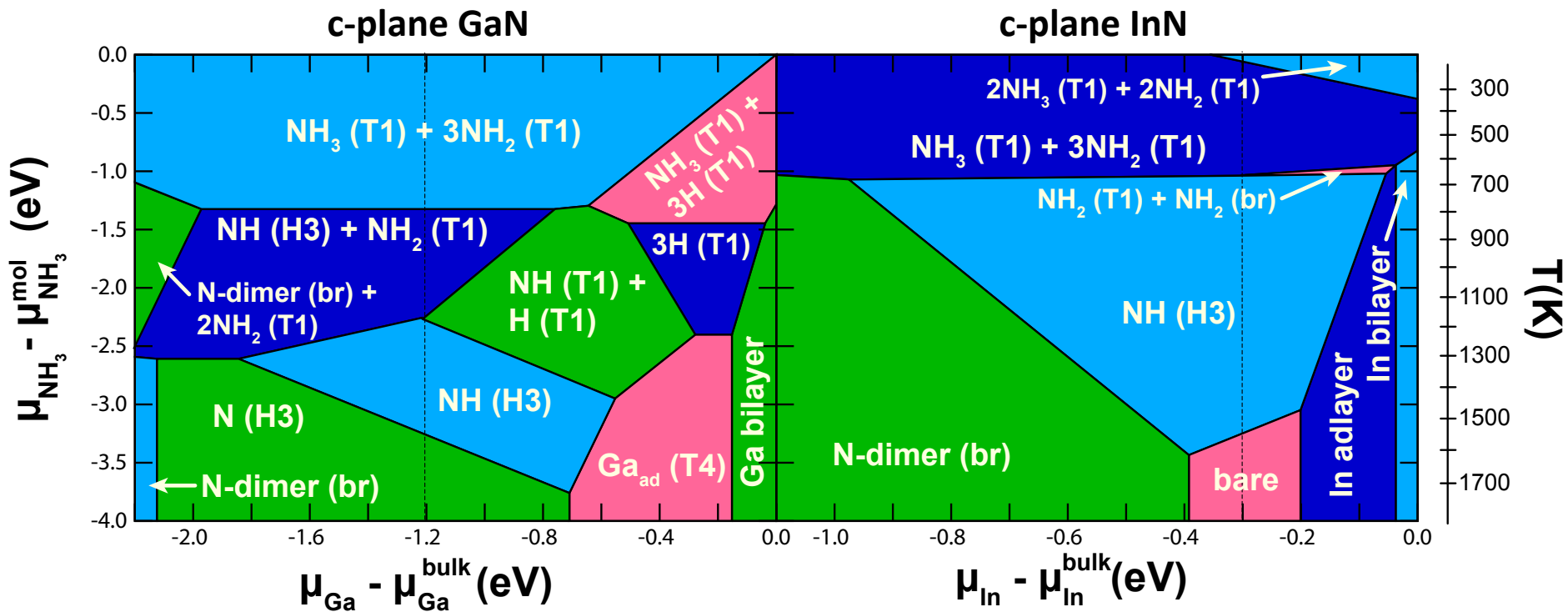
- **What are the intermediate nitrogen species?**

- First principle calculations
- Additional *in-situ* probes



Phase Diagrams at Finite Temperatures

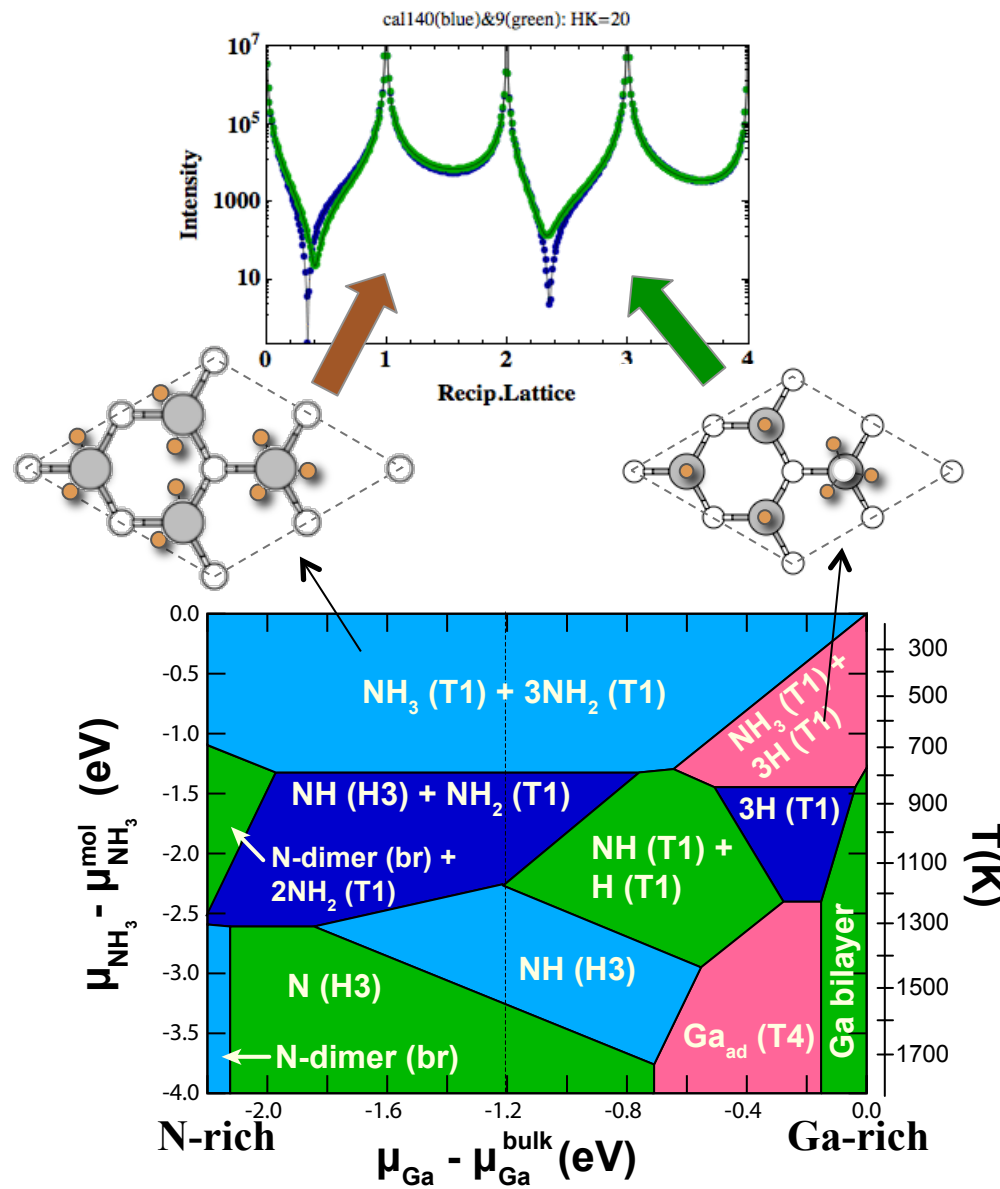
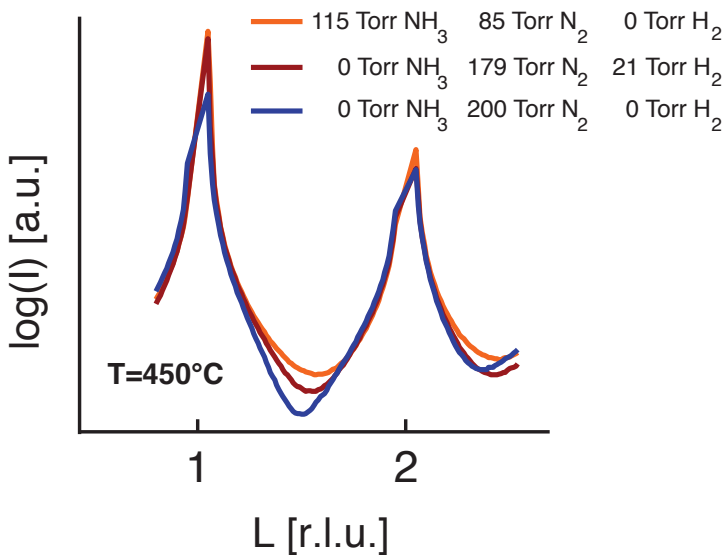
- Many possible structures depending on the chemical potential (μ)
- Surprisingly, some structures do not obey electron-counting rule
- Can we identify these structures experimentally?



W.Walkosz, P. Zapol and G. B. Stephenson, *Phys. Rev. B* 85, 033308 (2012)

CTR Analysis of Structures

- First Principle can be used to predict CTRs for each phase
- Can we see these changes with *in-situ* x-rays ?
- Have not found unique solutions



W. Walkosz, et al. PRB 85, 033308 (2012)

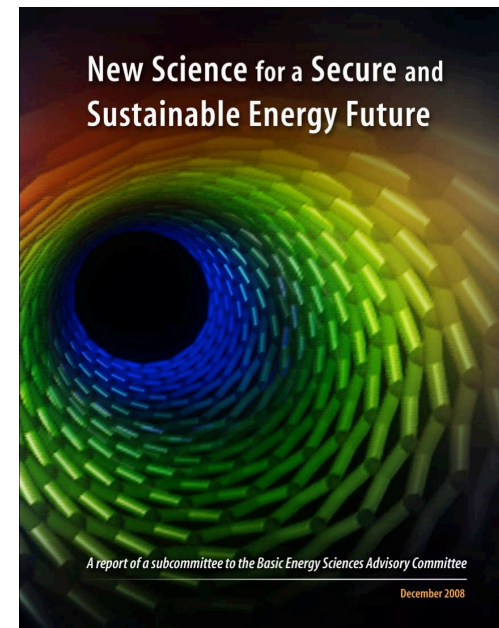
Fundamental Questions in Materials Science

What materials are present?

Where are the materials located?

When do crucial transformations and processes occur?

Why does a material have its structure and properties?



Advanced x-ray techniques provide unique information by looking into and through complex materials and devices.

Coupled with theory and advanced computing capabilities, this information enables a detailed understanding of material processing technologies and device physics.

Non-Perturbative Measurements using Minimum Photon Approaches

■ **Perturbation Limits**

- General physics of x-ray interactions (e.g. cross-sections)
- Perturbation limits of soft and hard matter
- Imaging resolution versus dose

■ **Extracting maximum information from each photon**

- Better algorithms
- Improved optics
- Advanced detectors

■ **Integrated approaches to solving scientific problems**

- X-ray measurements
- Theory and large scale simulation
- Other probes (e.g. TEM, optical spectroscopy)



Atomic Resolution, Ultrafast X-Ray Speckle from Liquids

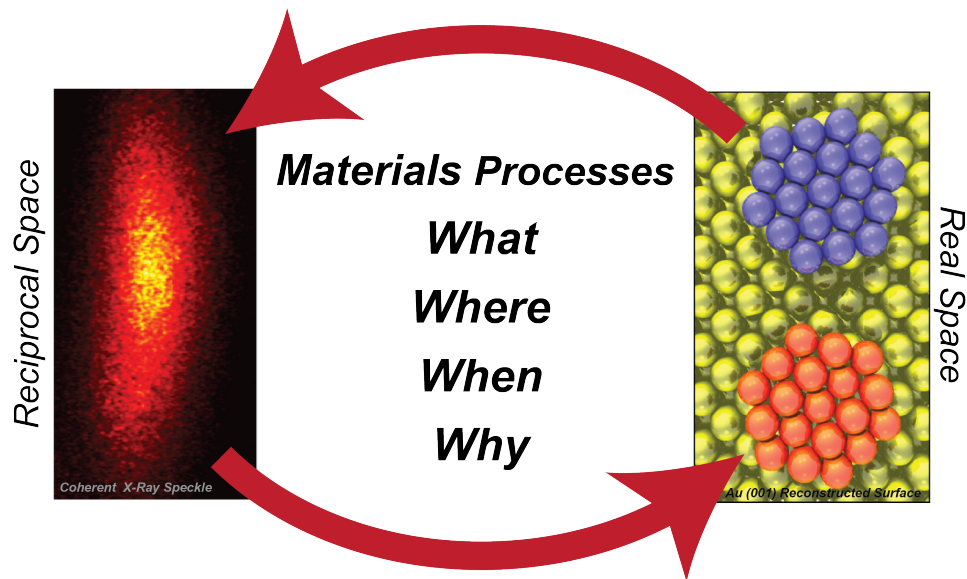
Paul Fuoss, Stephan Hruszkewycz,
Stephan Rosenkranz, Bernard Adams and
Brian Stephenson, *Argonne National
Laboratory*

Mark Sutton, *McGill University*

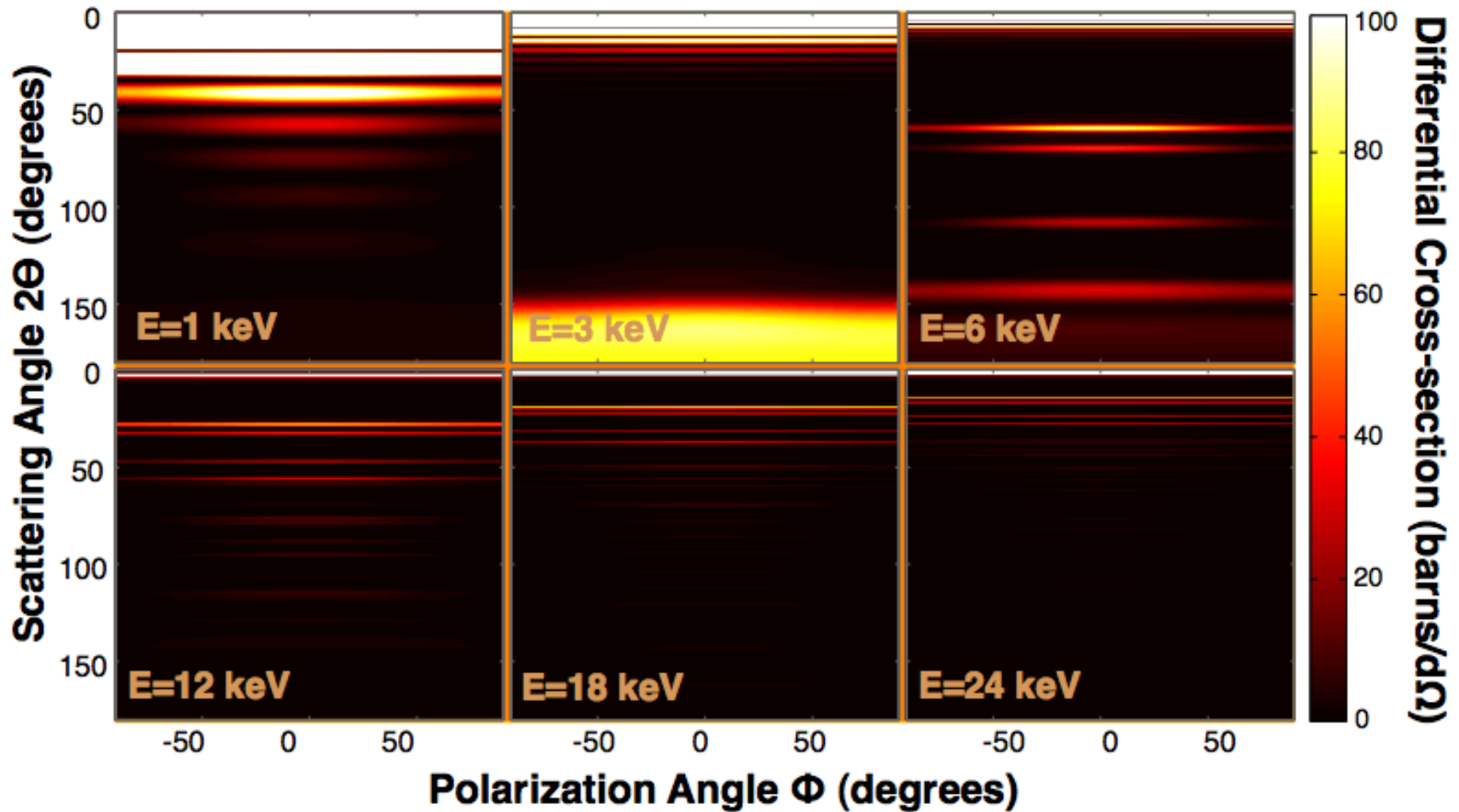
Karl Ludwig, *Boston University*

Aymeric Robert, Dave Fritz, Marcin
Sikorski, Sooheyong Lee, Diling Zhu,
Marco Cammarata and Henrik Lemke,
SLAC National Accelerator Laboratory

Christian Gutt, Wojciech Roseker and
Gerhard Grubel, *Deutsches Elektronen-
Synchrotron*



Scattering Calculations: Cross-Section of a Copper



Scattering Considerations: Basic Equation

Now we'll develop the x-ray scattering in more detail because that strongly impacts experimental design. The basic scattering equation is:

$$d\sigma(\vec{Q}) = \left(\frac{e^4}{m^2 c^4} \right) \sum_{i=1}^{N_{atoms}} \sum_{j=1}^{N_{atoms}} f_i(\vec{Q}) f_j(\vec{Q}) e^{-\vec{Q} \cdot \vec{R}_{ij}} d\Omega$$

where

\vec{Q} = the difference between the exit and incident wavevectors

\vec{R}_{ij} = the vector connecting atoms i and j

f_i = the atomic scattering factor of atom i

